

# Precision radiation detectors for cutting edge research projects developed at the MPS Semiconductor Lab

Jelena Ninkovic

- MPS Semiconductor Lab
- Devices & Selected Applications

- MPS Semiconductor Laboratory (in German: MPG Halbleiterlabor - HLL)



Located in the south-east of Munich on the Siemens Campus in Neuperlach  
30 employees: scientists, engineers and technicians  
+ guest scientists, engineers and students



MPG HLL is the only lab worldwide doing fully depleted silicon radiation sensors with integrated electronics optimized for different scientific projects

## ● The MPG HLL history

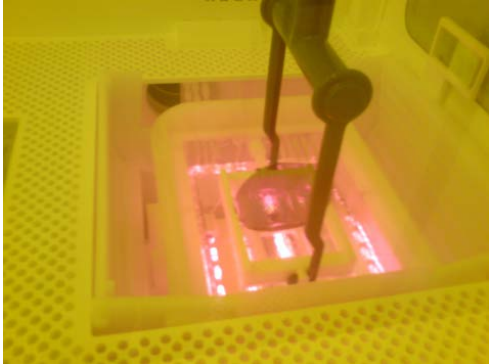
- Started 1983 – NA11 experiment
- 6 inch process line from 2001
- Till 2013 joined lab of the MPI for Physics  
MPI for Extraterrestrial Physics
- From 2013 - Central Unit of the Max-Planck-Society
  - Open to all Max Planck Institutes
  - and to External partners

*Technology - Devices - Projects*



# ● Inside HLL – Sensor Fabrication

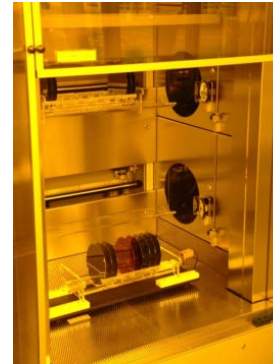
*cleaning*



*lithography*



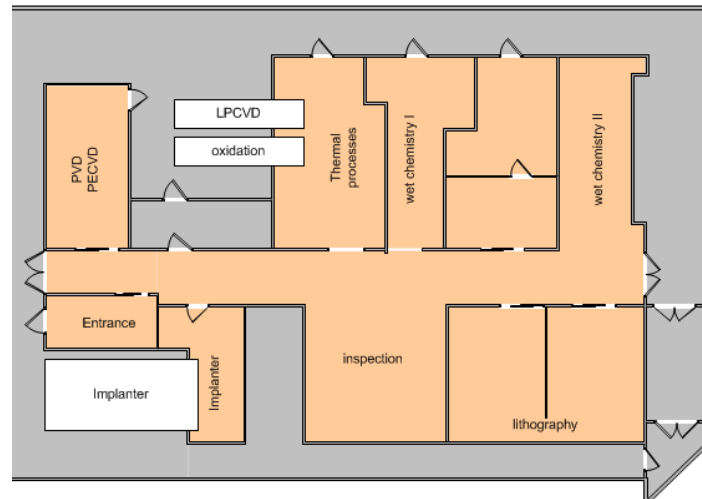
*thermal*



*inspection*



*implantation*



6" Si full processing line  
class 1000 to class 1 in certain areas



# ● Inside HLL – Sensor Fabrication

*plasma and sputter*



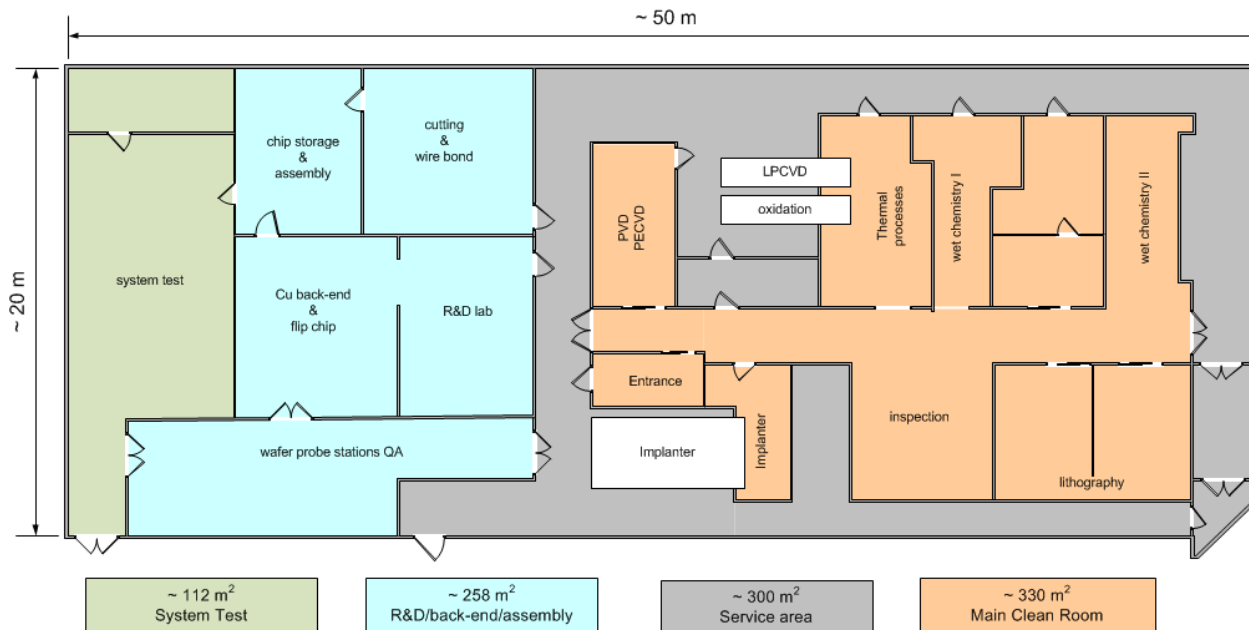
*Cu line*



*flip chip*

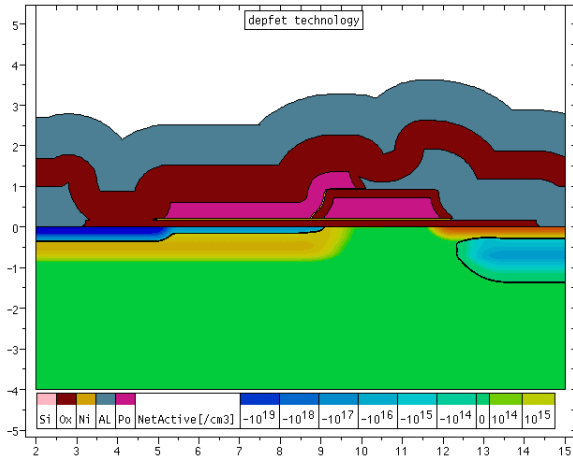


*assembly and test*

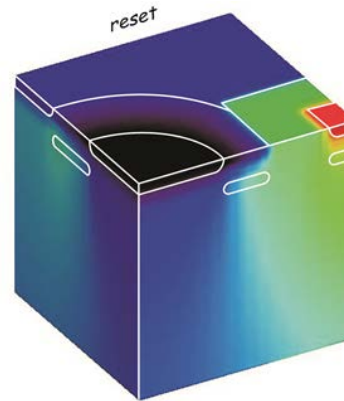


# ● Inside HLL – Sensors and Systems: Design & Test

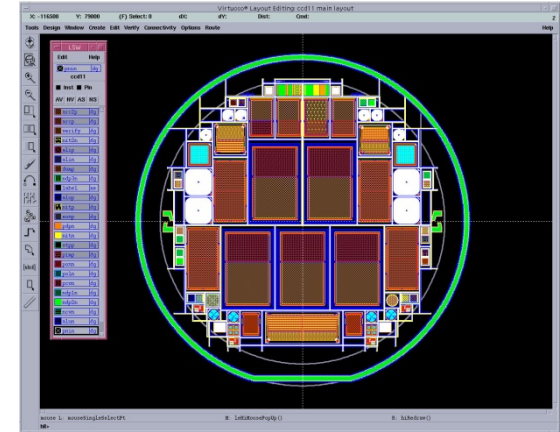
Process simulation



Device simulation, 2D and 3D



State-of-the-art layout tools



Wire bonding, hybrid assembly



@ HLL:

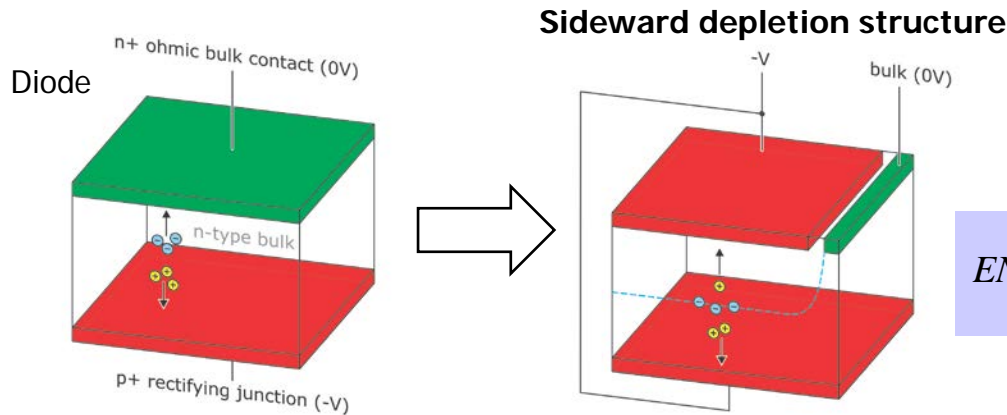
- sensor design and fabrication
- interconnection
- system/camera design and test

System test facilities



● Goal : High SNR

• Decrease noise

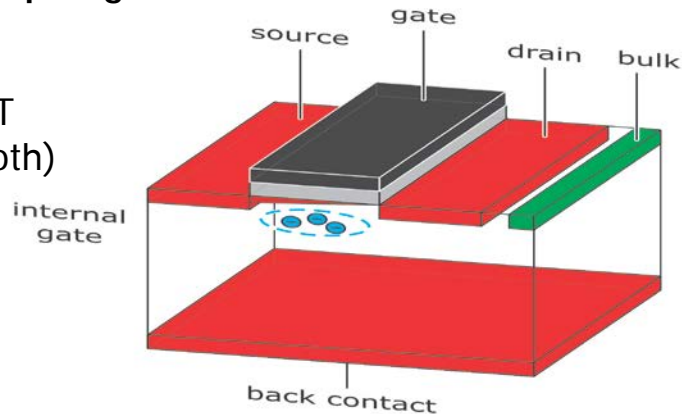


$$ENC = \sqrt{\alpha \frac{2kT}{g_m} C_{tot}^2 A_1 \frac{1}{\tau} + 2\pi a_f C_{tot}^2 A_2 + q I_L A_3 \tau}$$

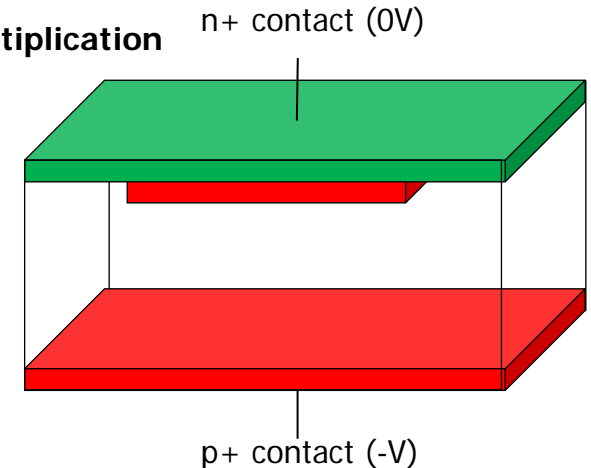
• Amplify signal

First Amp stage in the sensor

DEPFET  
(has both)



Avalanche multiplication

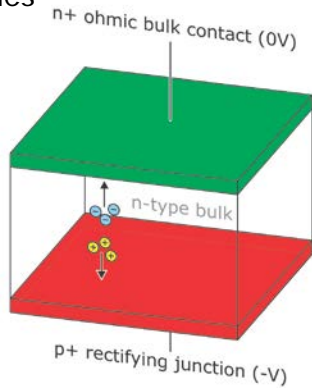




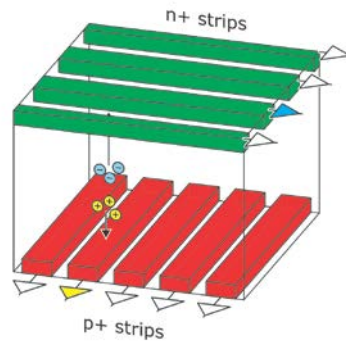
# ● Devices @ HLL

## ● Building blocks

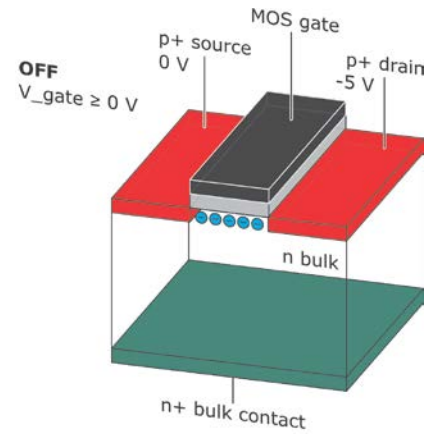
### Diodes



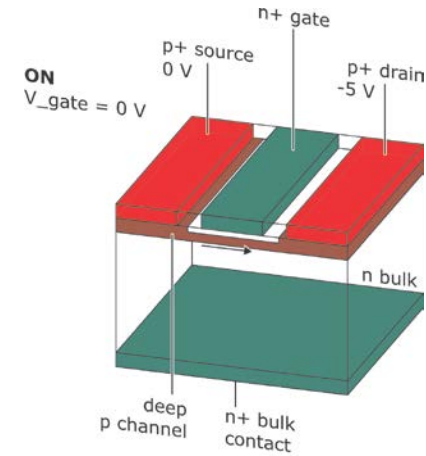
### Strip detectors



### MOSFETs

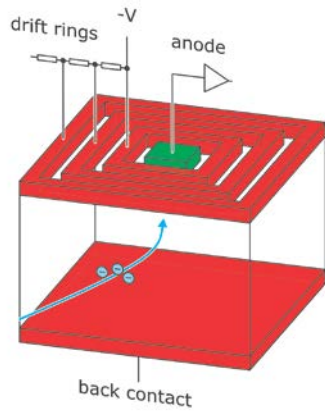


### JFETs

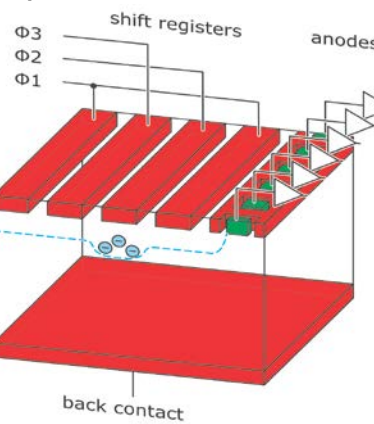


## ● Devices

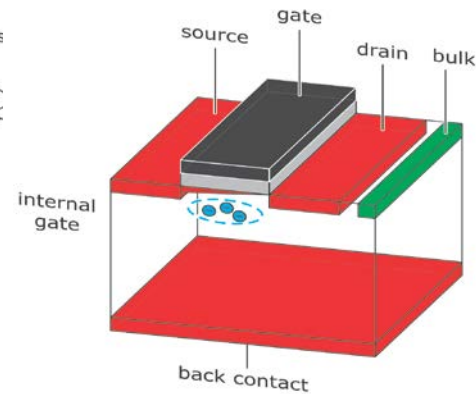
### Silicon drift detectors (SDD)



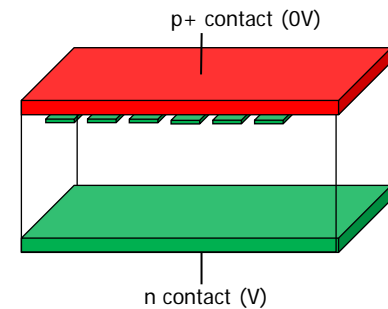
### pnCCDs



### DEPFETs

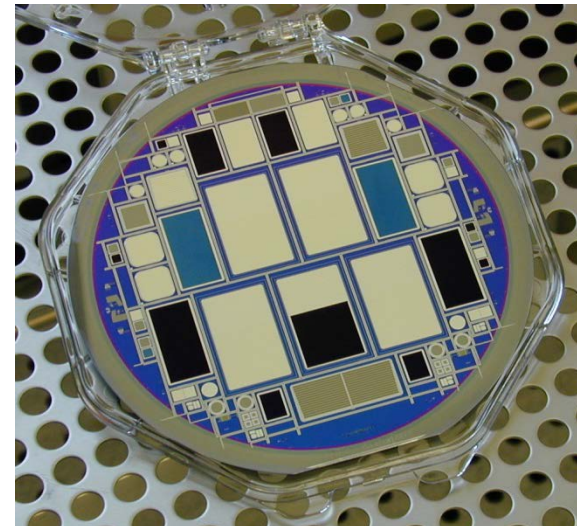
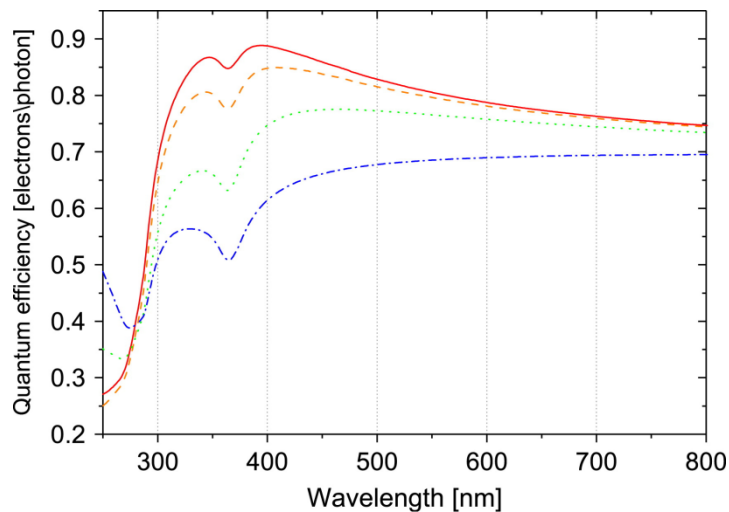
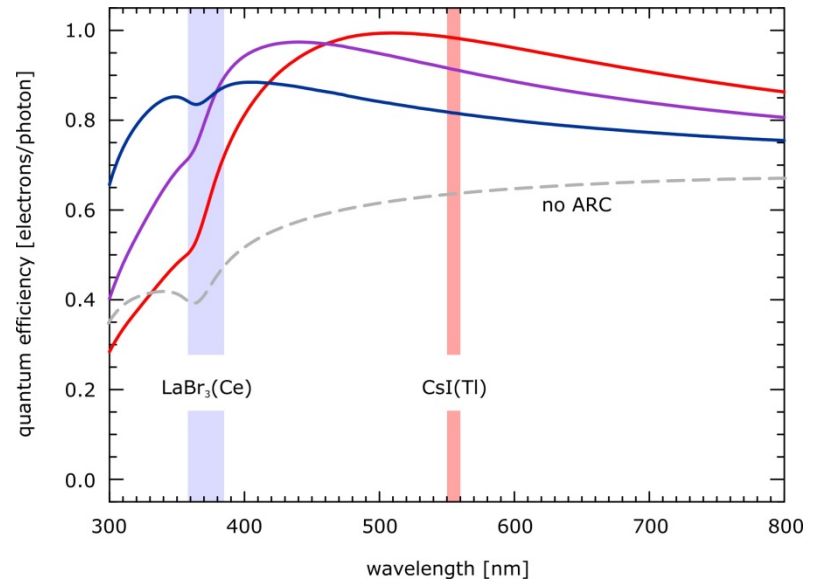


### SiMPI



# ● Entrance window engineering – application optimization

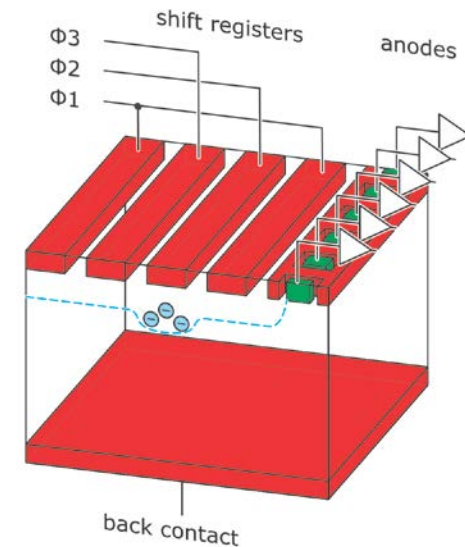
- anti-reflective coating (ARC)
  - ▷ sequence of dielectric layers deposited on the entrance window
  - ▷ variation of material and thickness
  - ▷ transmittance tuning to application needs
- polymer passivation
  - ▷ mechanical protection
  - ▷ optical coupling



# pnCCDs

Proposed by Lothar  
Strüder et al., 1987

- ▷ definition of potential pockets by differently reverse-biased diodes
- ▷ charge transport by periodic clocking of shift registers
- ▷ **column-parallel readout** → high frame rate (5 msec @ 200 pixel)
- ▷ integrated 1st FET (1 / column) → **low noise** (3el. ENC)
- ▷ backside illuminated, **fully depleted** → **high quantum efficiency**



- format ~ cm<sup>2</sup> ... **wafer scale**
- thickness 450  $\mu\text{m}$
- **pixel size 36 ... 150  $\mu\text{m}$**

## Applications

- X-ray imaging & spectroscopy
- optical light imaging



- Projects using pnCCDs developed and fabricated @ MPG HLL

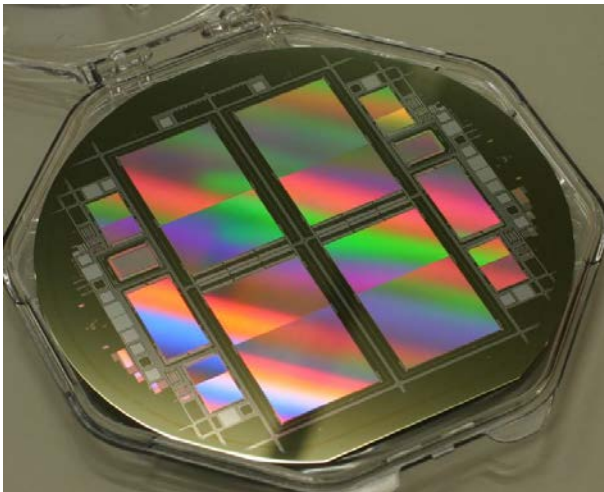
- X-ray imaging spectroscopy in space – eROSITA
- Solar Polarimetry - Fast Solar Polarimeter
- Synchrotron radiation detection – sensors for FELs

## ● pnCCDs for eROSITA

„ extended ROentgen Survey with an Imaging Telescope Array “

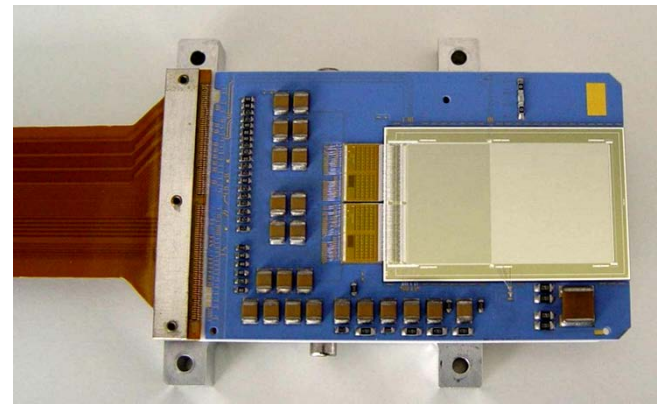
The main scientific goals are:

- map out the large scale structure in the Universe for the study of cosmic structure evolution
- Black Holes in nearby galaxies and many (up to 3 Million) new, distant active galactic nuclei and
- physics of galactic X-ray source populations, like pre-main sequence stars, supernova remnants and X-ray binaries.



3cm x 3cm pnCCDs still on Si-Wafer.  
The pn CCDs have  $384 \times 384$  pixels in both image and frame store area.

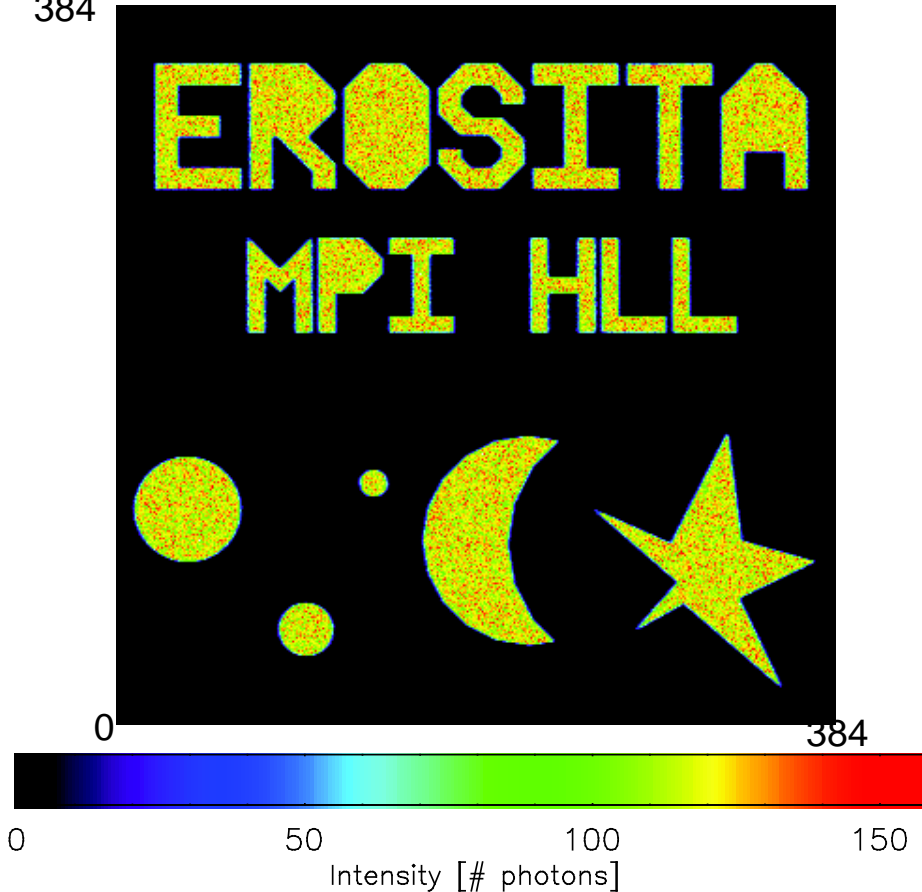
Pixel size:  $75 \times 75 \mu\text{m}^2$ .  
Frame time: 50 msec



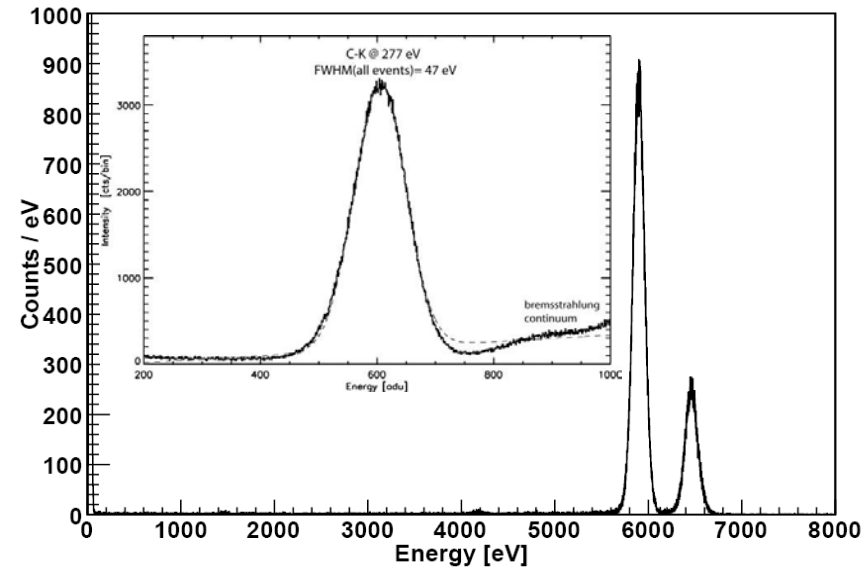
(collaboration partner MP Extraterrestrial Physics)

# eROSITA pnCCD-Module

384



Shadow image of a 450  $\mu\text{m}$  thick silicon baffle with an  $^{55}\text{Fe}$  source mounted directly in front of the sensor



Measurements at C Ka (277eV) and Mn Ka (5,9 keV) on flight- CCDs (2cm  $\times$  2cm) show the expected energy resolution and low energy response.

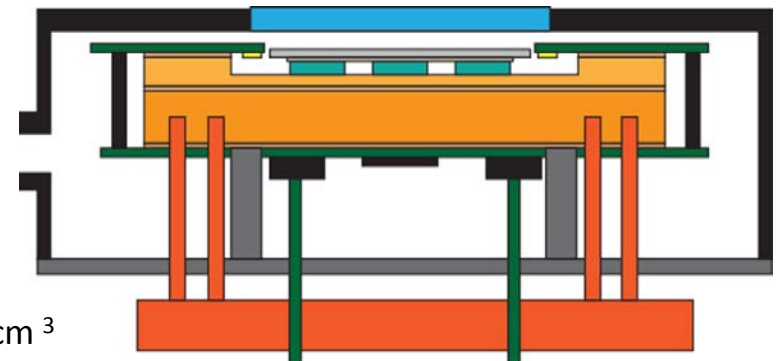
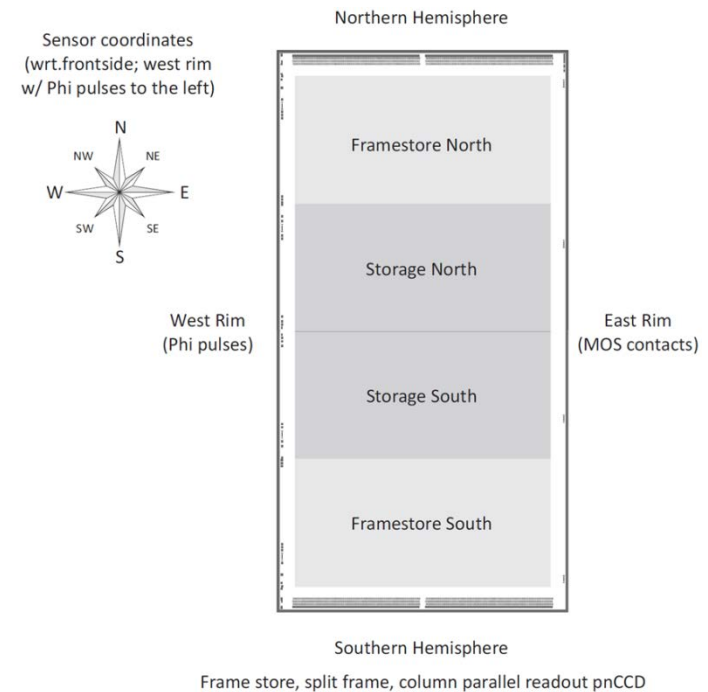


# ● Small pixel pnCCD @ HLL

Motivation: development of a sensor for Fast Solar polarimetry  
(collaboration partner MP Solar System Research)

## Device characteristics:

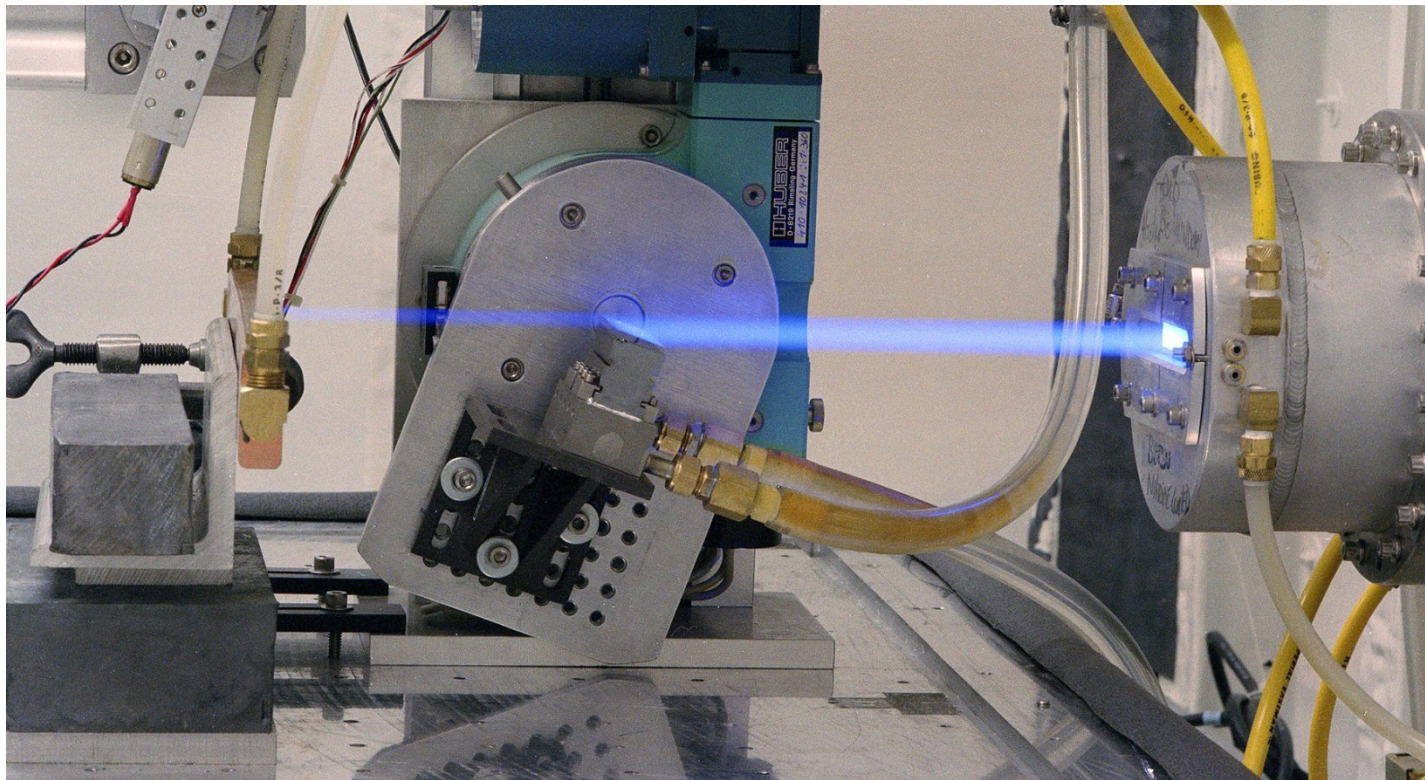
- pnCCD concept:
  - Backside illuminated,
  - frame store,
  - split frame,
  - column-parallel readout
- Format: **1k x 1k** storage, 2 x 1 k x 0.5 k framestore
- Pixel size: **36 x 36**  $\mu\text{m}^2$
- Total sensitive area: 36.8 x 73.3  $\text{mm}^2$
- Total chip size: 4.2 x 8.1  $\text{cm}^2$
- Optimized for **optical wavelength** using ARC
- Operating temperature: -35°C (target)
- Target operating frame rate: **400 Hz** ( $\sim 4 \mu\text{s}$  /row)
- Data rate: 840 Mbyte / s (16 bit)



Compact vacuum-tight camera housing  $\sim 18 \times 25 \times 10 \text{cm}^3$

- FEL radiation detection

- Sensors for LCLS (collaboration partner MP Extraterrestrial Physics)



Synchrotron light from the National Synchrotron Light Source (NSLS), Brookhaven

## ● Requirements in FEL radiation applications

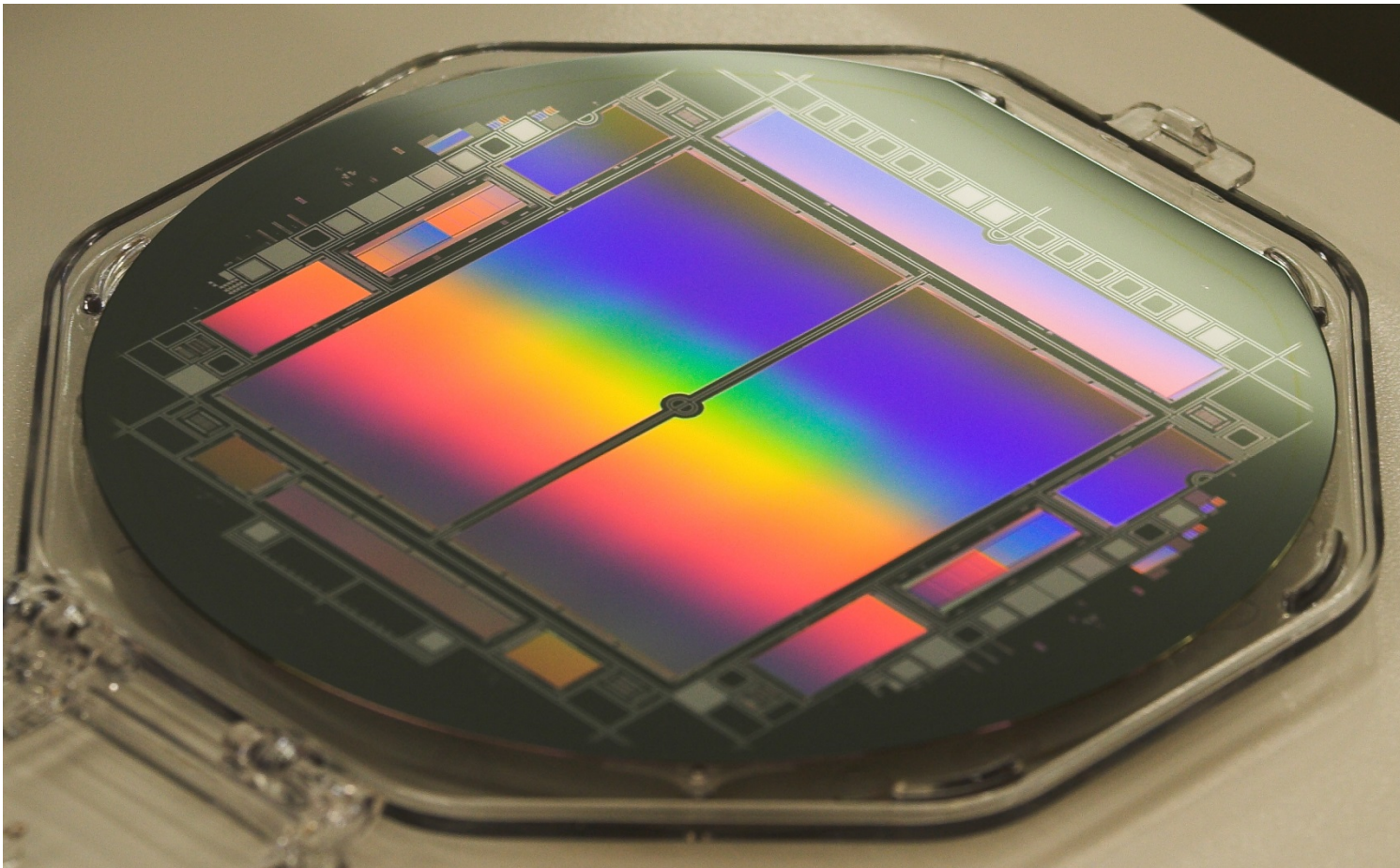


### Requirements of the LCLS

	LCLS	pnCCD
single photon resolution	yes	yes
energy range	$0.05 < E < 24$ (keV)	$0.05 < E < 25$ [keV]
pixel size ( $\mu\text{m}$ )	100	75 (150)
sig.rate/pixel/bunch	$10^3$ ( $10^5$ )	$10^4$
quantum efficiency	$> 0.8$	$> 0.8$ from 0.3 to 12 keV
number of pixels	512 x 512 (min.)	1024 x 1024
frame rate/repetition rate	10 Hz - 120 Hz	up to 250 Hz
Readout noise	$< 150 e^-$ (rms)	$< 30 e^-$ (rms) (2 $e^-$ possible)
cooling	possible	- 20° C optimum room temperature possible
vacuum compatibility	yes	yes
preprocessing	no (yes) ?	possible upon request



- Large area pnCCDs

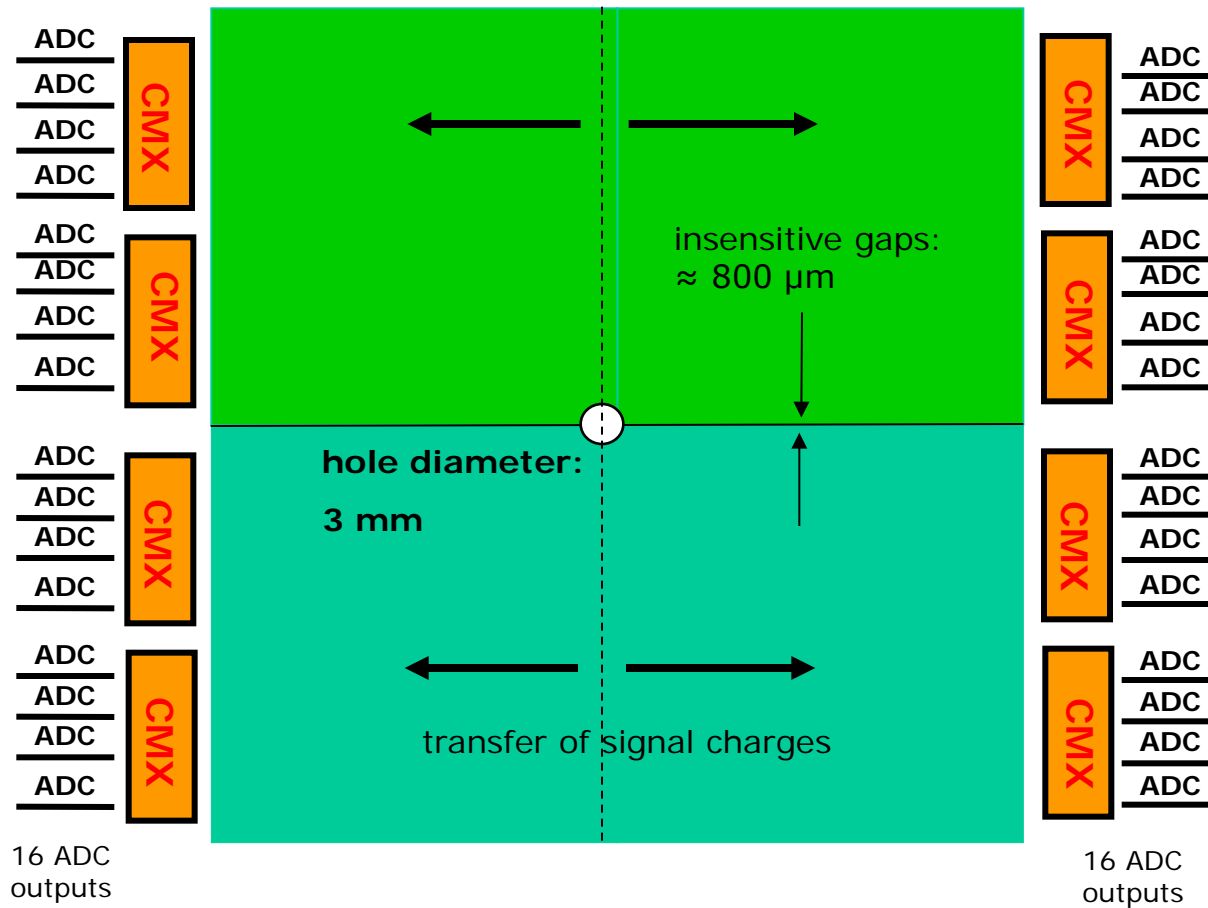


- ▷ Large area pnCCDs: 30 cm<sup>2</sup>
- ▷ 1024 x 512 pixel of 75 x 75 μm<sup>2</sup>
- ▷ 3.7 x 7.8 cm<sup>2</sup>

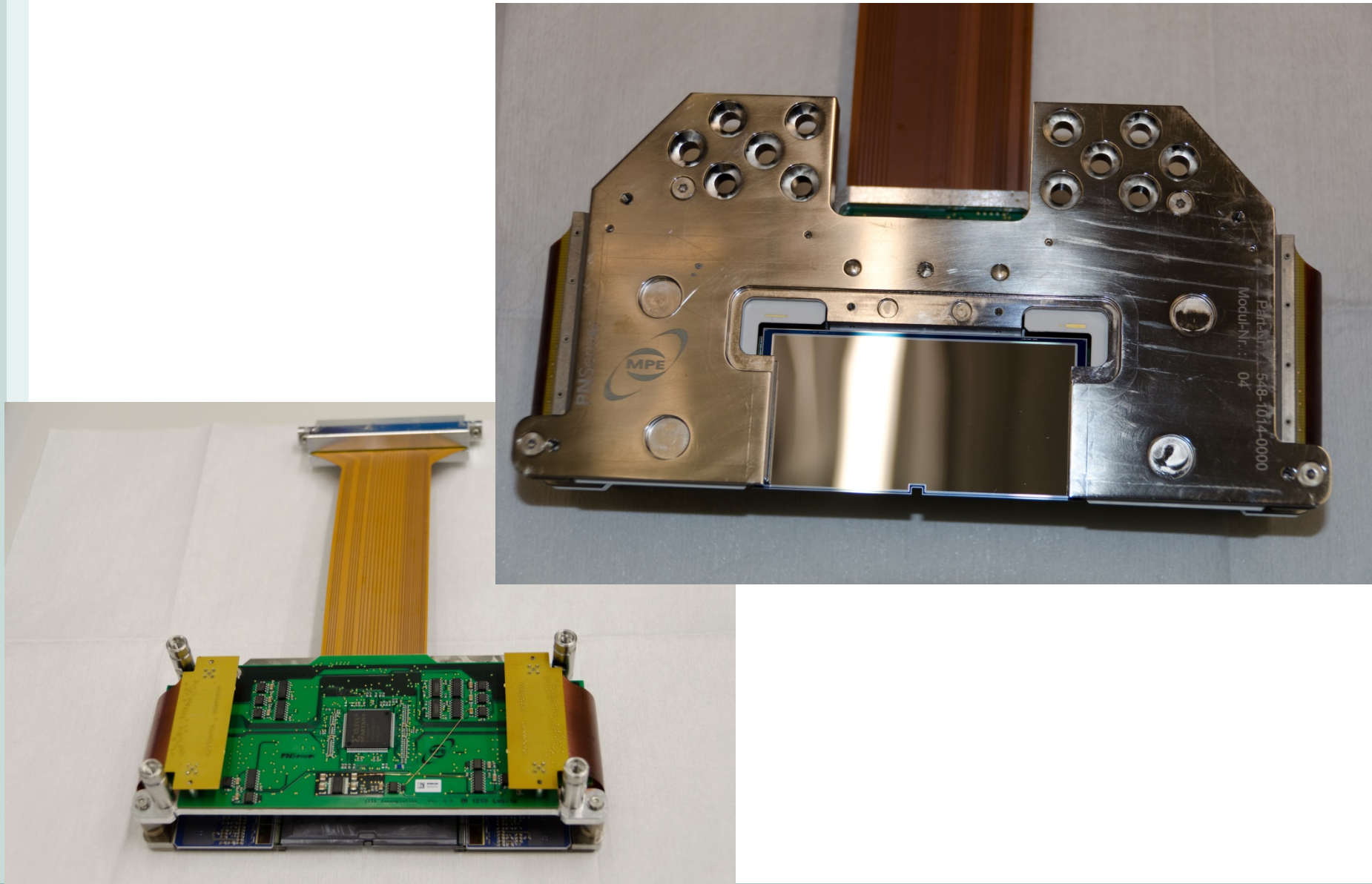


# ● Detectors for LCLS

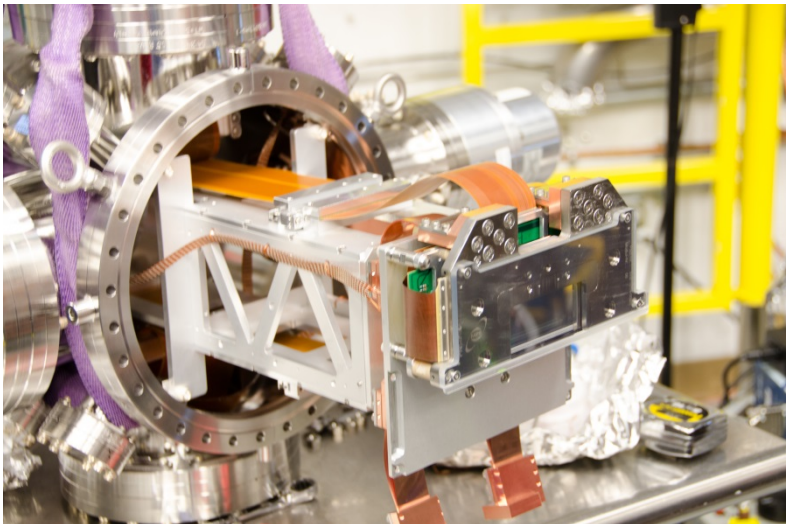
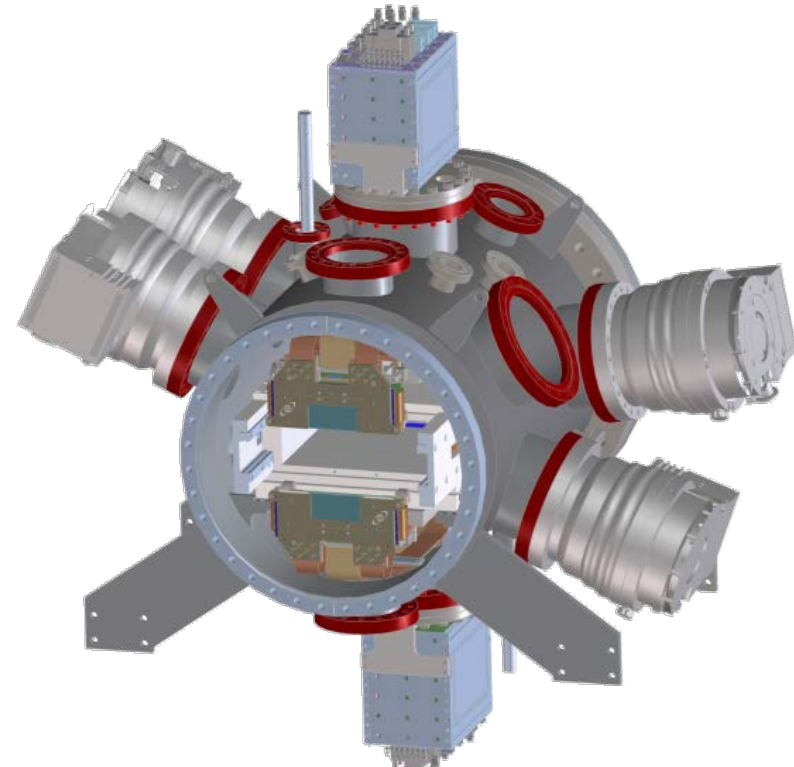
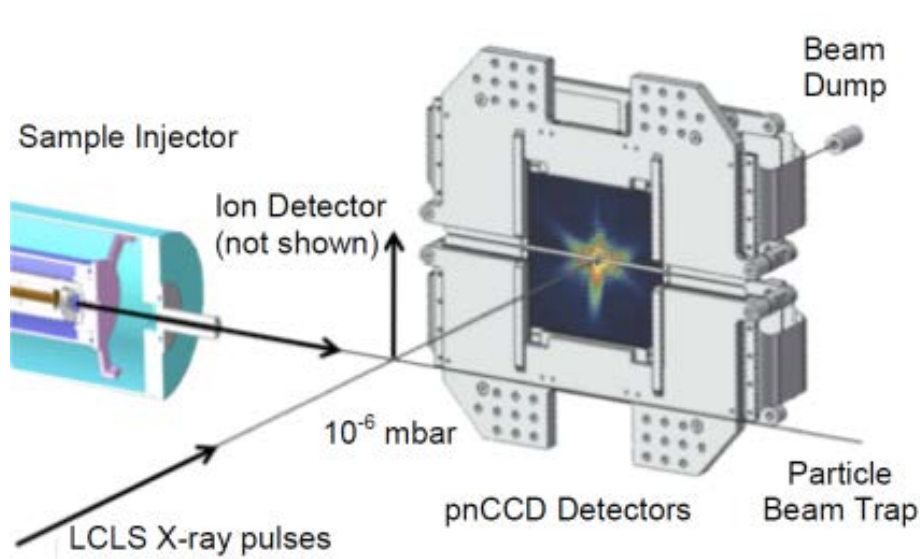
- Full sensitive area of system 59 cm<sup>2</sup>
- 1024x 1024 pixels of 75 x 75 μm<sup>2</sup>
- Readout time per frame 4 ms - 250 frames / s



- LAMP module



- Lamp system @LCLS





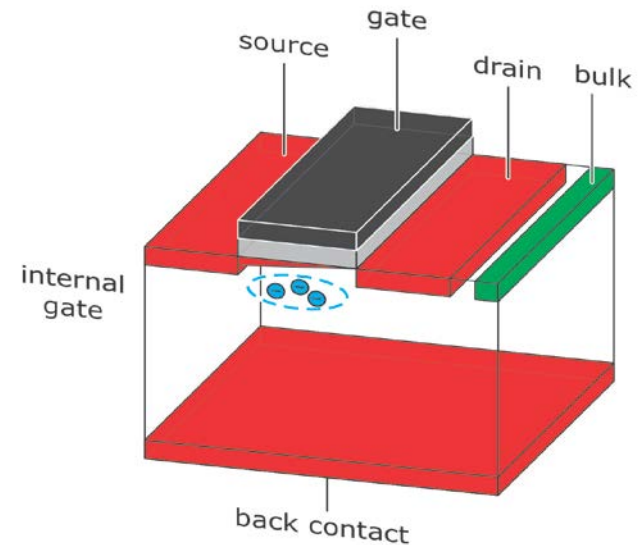


# DEPFETs

p-MOSFET on fully depleted n-substrate

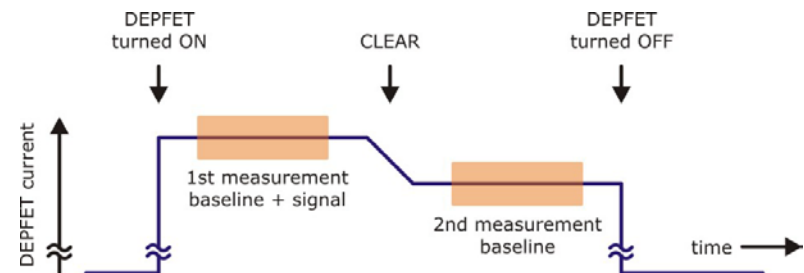
- **fully depleted** sensitive volume
  - fast signal rise time ( $\sim$ ns), small cluster size
  - no stitching, 100% fill factor
- **Charge collection in "off" state**, read out on demand
  - potentially low power device
  - Non destructive readout
- **internal amplification**
  - charge-to-current conversion (300 pA/el.)
  - large signal, even for thin devices
  - r/o cap. independent of sensor thickness (20 fF)

Proposed by  
Josef Kemmer &  
Gerhard Lutz, 1987

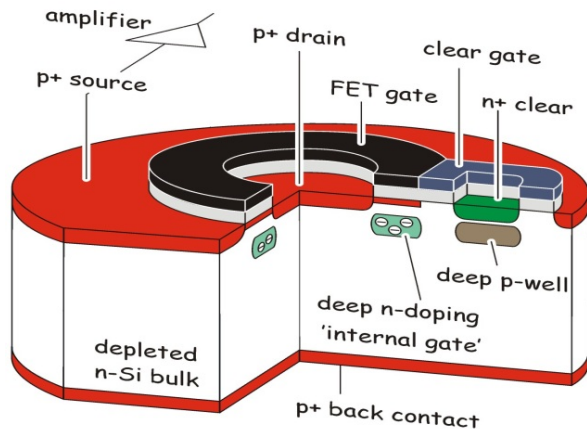


Applications:

- unit cell of active pixel sensor
- integrated readout device of SDD, pnCCD, ...

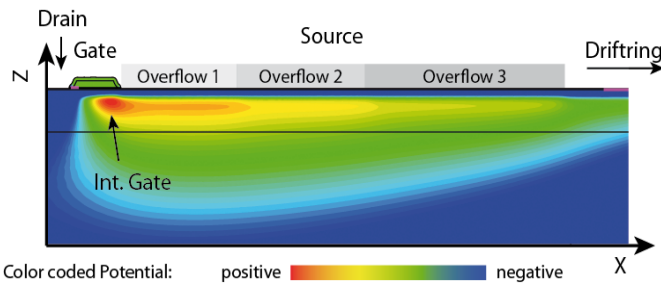


# DEPFET classes



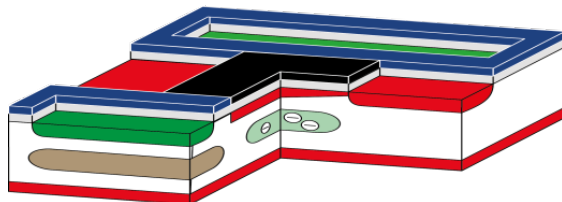
## Low noise: Spectroscopic X-Ray imaging

pixel size: 100 $\mu\text{m}$ , with drift rings several 100s of  $\mu\text{m}$   
 read out time per row: few  $\mu\text{s}$   
 Noise:  $\approx 4$  el ENC  
 fully depleted, the thicker the better  $\rightarrow$  large QE for higher E



## High Dynamic range, ultra-fast read-out

**DEPFET Sensor with Signal Compression**  
 Sensitivity to single photons and high dynamic range  
 pixel size:  $\sim 200 \mu\text{m}$   
 hybrid sensor : 1-to-1 bonded to readout chip



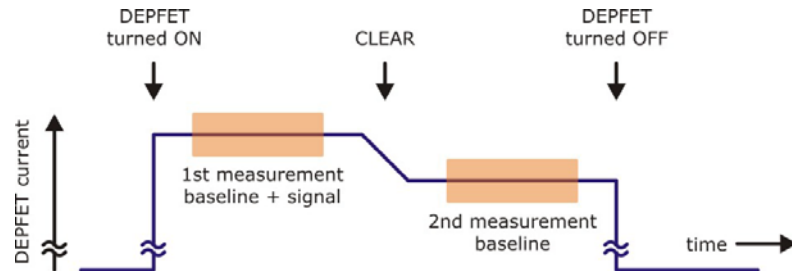
## Thin & small pixel: vertex, low E electron detectors (TEM)

pixel size: 20 $\mu\text{m}$ ...75 $\mu\text{m}$   
 read out time per row: 25ns-100ns  
 Noise:  $\approx 100$  el ENC  
 thin detectors: 50 $\mu\text{m}$ ...75 $\mu\text{m}$   $\rightarrow$  still large signal: 40nA/ $\mu\text{m}$  for MIP

# DEPFET detectors

## DEPFET readout

### ▷ readout sequence



### ➤ Double sampling

- 1st measurement: signal + baseline
- clear: removal of signal charges
- 2nd measurement: baseline
- difference = signal

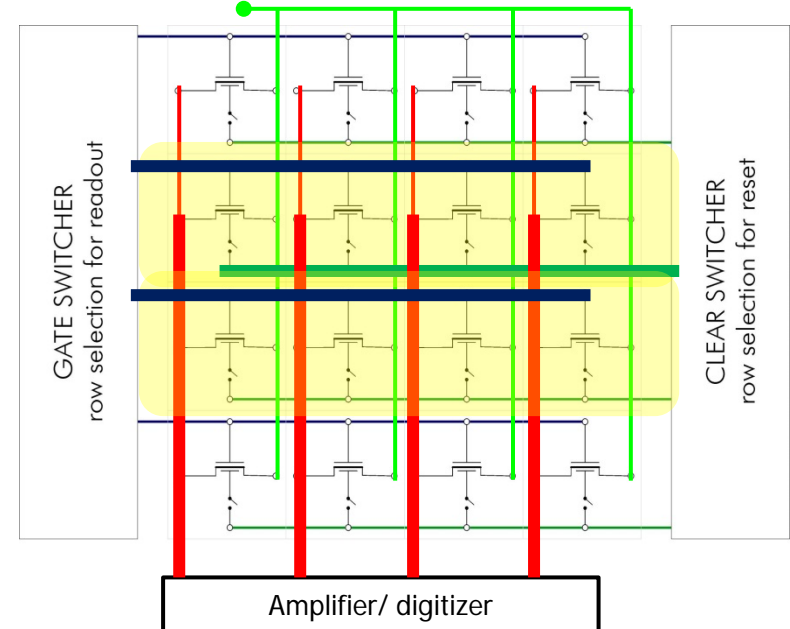
### ➤ Single sampling

- Measure pedestals and store
- Read once and clear

### ▷ active pixel sensor operation

- horizontal supply lines, row selection
- vertical signal lines
- 1 active row, other pixels integrating

### Rolling shutter read out



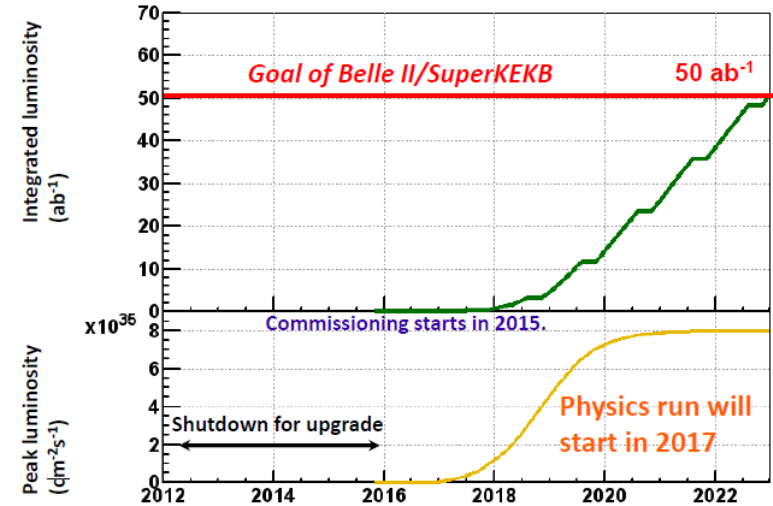
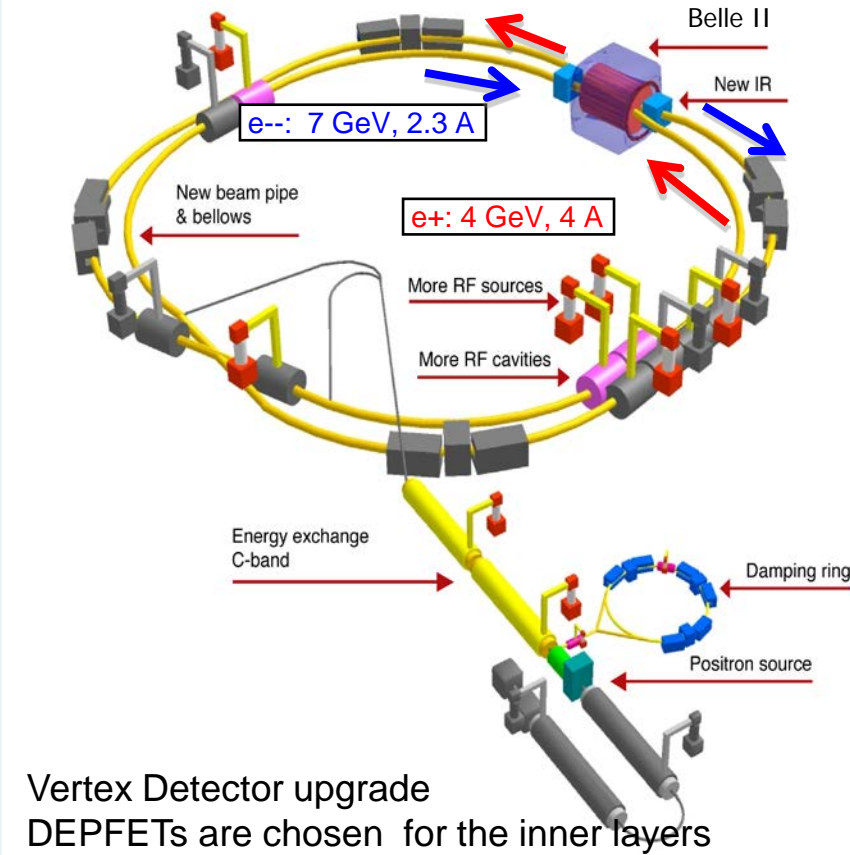
- Projects using DEPFETs developed and fabricated @ MPG HLL

- Vertex detectors for high energy physics experiments
- X-ray fluorescence spectrometer for MIXS on BepiColombo
- X-ray imaging spectroscopy - ATHENA mission – Wide Field Imager (WFI)
- FEL radiation detection – sensors for European XFEL
- Electron Detectors - 80k low E electron detectors

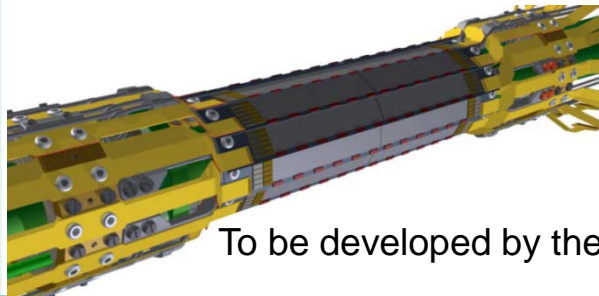


# BELLE II @ SuperKEKB

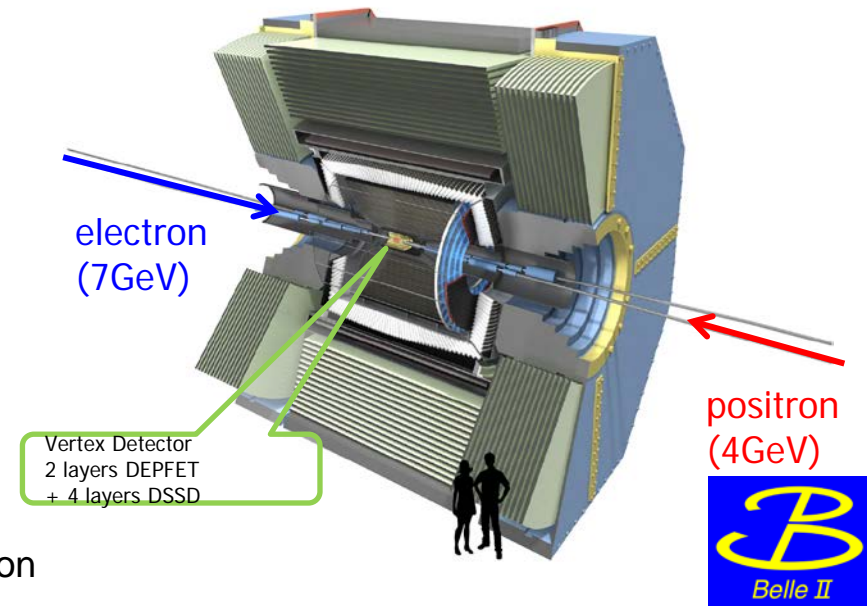
## SuperKEKB luminosity projection



Vertex Detector upgrade  
DEPFETs are chosen for the inner layers

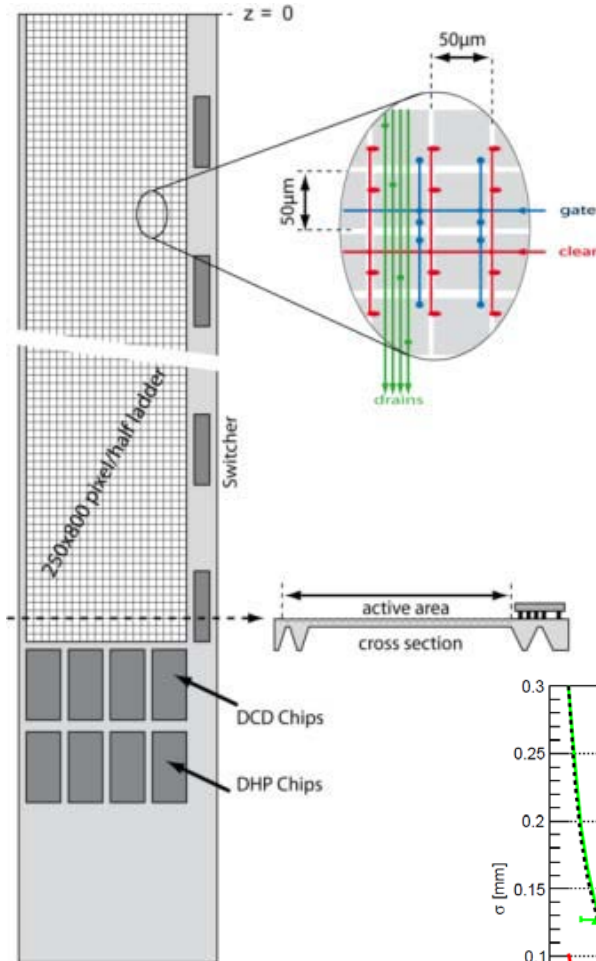


To be developed by the DEPFET collaboration



# DEPFETs for BELLE II vertexing - Module

All silicon module

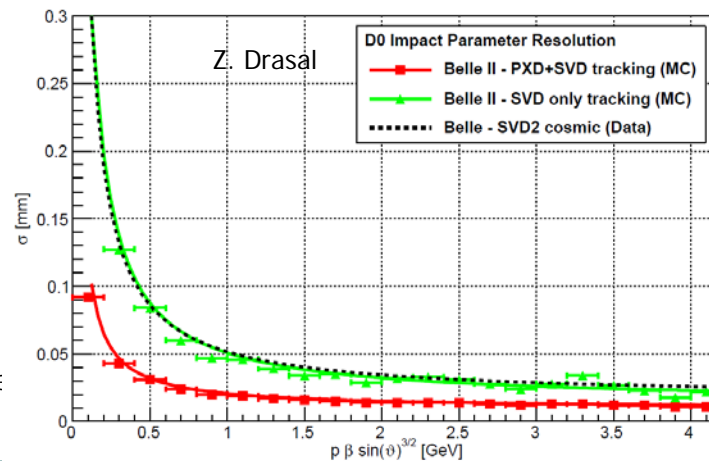


### Requirements:

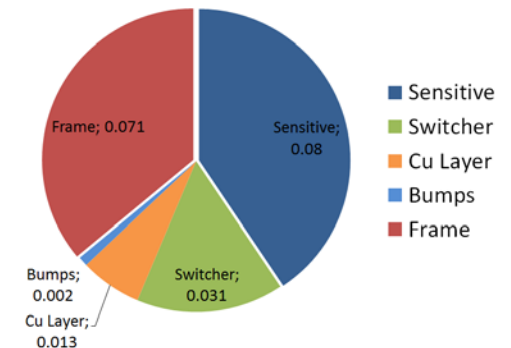
- Single point resolution **~ 10  $\mu\text{m}$**
- Radiation **~ 20 Mrad (10 years)**
- Material budget **0.2 %  $X_0$ /layer**
- Frame time **20  $\mu\text{s}$**



	Inner layer	Outer layer
# ladders	8	12
Sens. length	90mm	123mm
Radius	1.4cm	2.2cm
Pixel size	50x50 $\mu\text{m}^2$	50x75 $\mu\text{m}^2$
# pixels	1600(z)x250(R- $\phi$ )	
Thickness	<b>75 <math>\mu\text{m}</math></b>	
Frame/row rate	50 kHz/10 MHz	



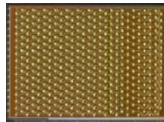
Material contribution 0.2%  $X_0$  measured



DCDB & SWB developed by UNI Heide  
DHP developed by UNI Bonn

# DEPFET all-silicon module

## DCDB (Drain Current Digitizer) Analog front-end



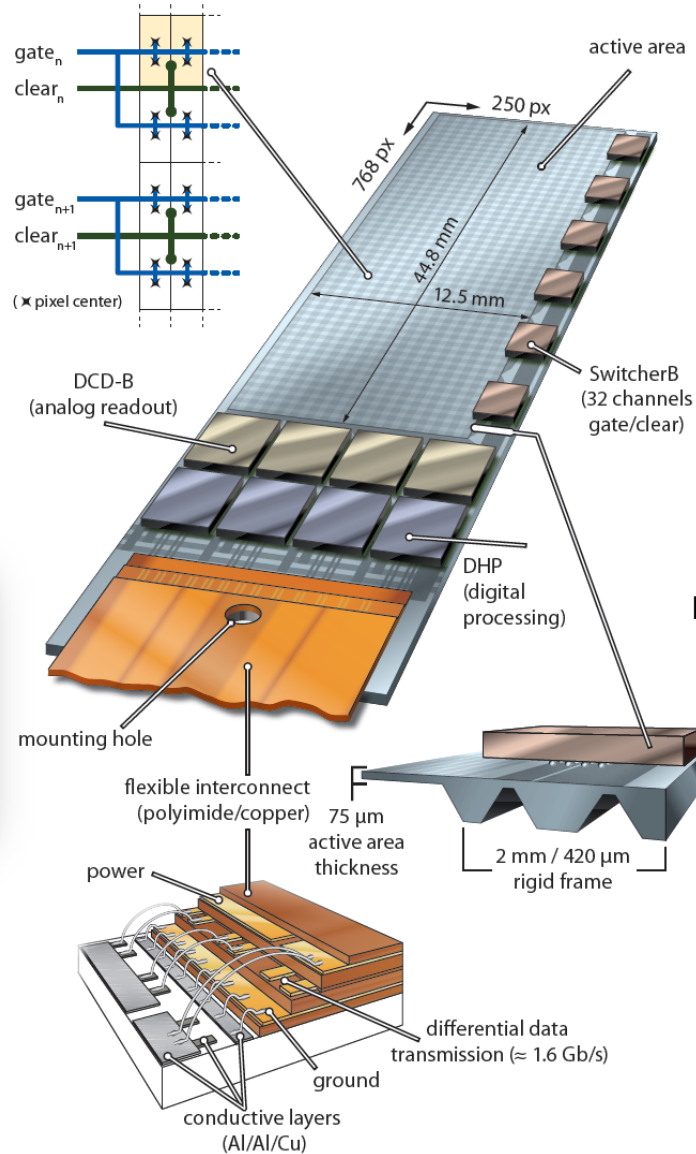
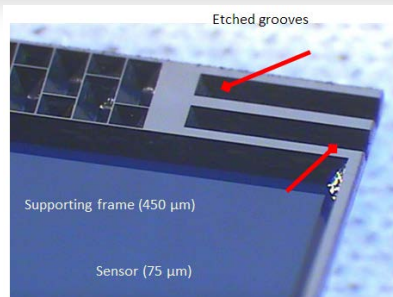
Amplification and digitization of DEPFET signals.

- 256 input channels
- 8-bit ADC per channel
- 92 ns sampling time
- UMC 180 nm
- Rad hard design

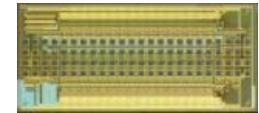
## Low mass vertex detectors

### MCMs with highest possible **integration!**

- ↳ Thin sensor area
- ↳ EOS for r/o ASICs
- ↳ Thin (perforated) frame with steering ASICs

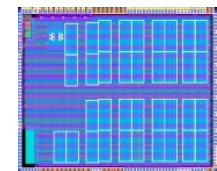


## SwitcherB - Row Control



- AMS/IBM HVCMOS 180 nm
- Size 3.6 × 1.5 mm<sup>2</sup>
- Gate and Clear signal
- 32x2 channels
- Fast HV ramp for Clear
- Rad. Hard proved (36 Mrad)

## DHP (Data Handling Processor) First data compression



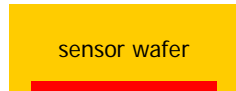
- IBM CMOS 90 nm (TSMC 65 nm)
- Size 4.0 × 3.2 mm<sup>2</sup>
- Stores raw data and pedestals
- Common mode and pedestal correction
- Data reduction (zero suppression)
- Timing and trigger control
- Rad. Hard proved (100 Mrad)



● Thin DEPFETs for BELLE II PXD

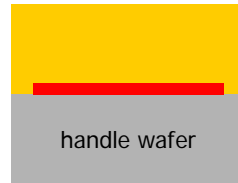


Thin (50µm-75µm) self-supporting all silicon module



sensor wafer

Process backside  
e.g. structured implant



handle wafer

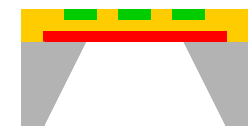
Wafer bonding  
SOI process



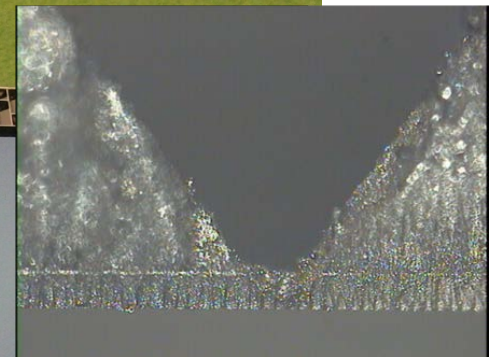
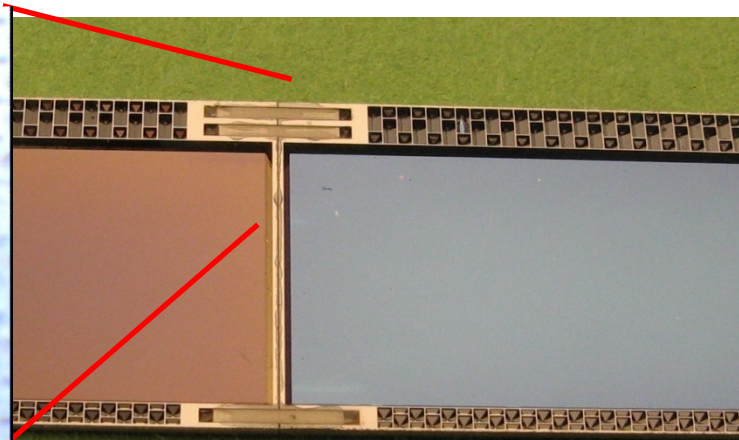
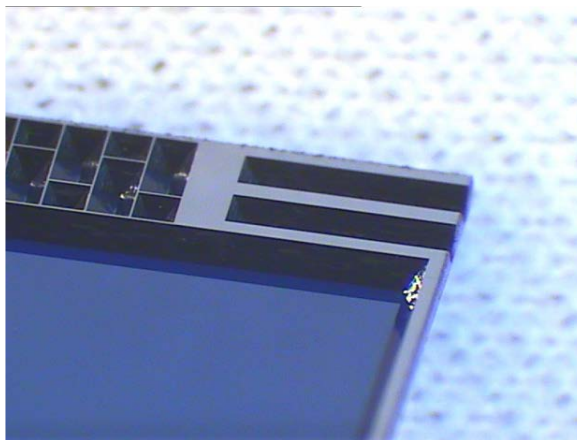
Thinning of top  
wafer (CMP)



Processing



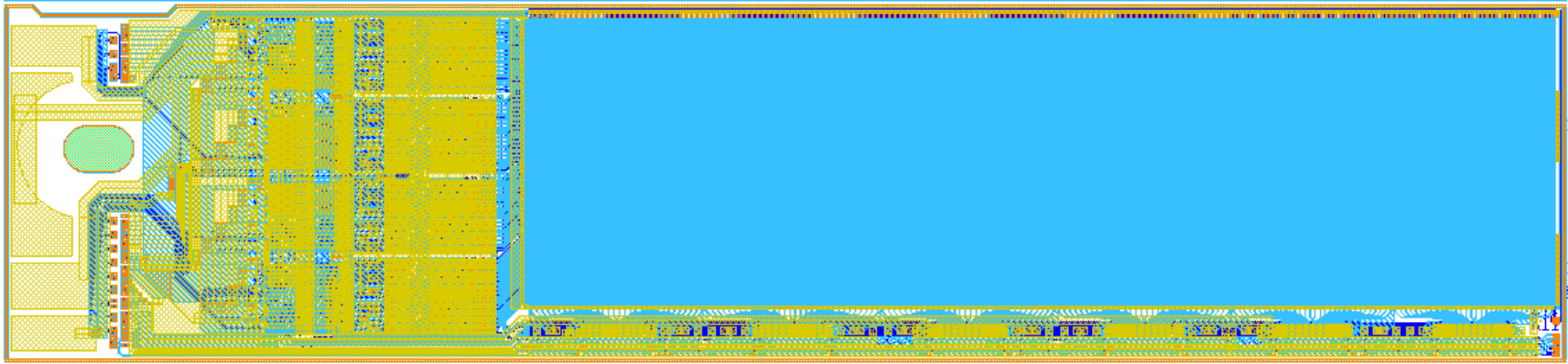
etching of handle  
wafer (structured)





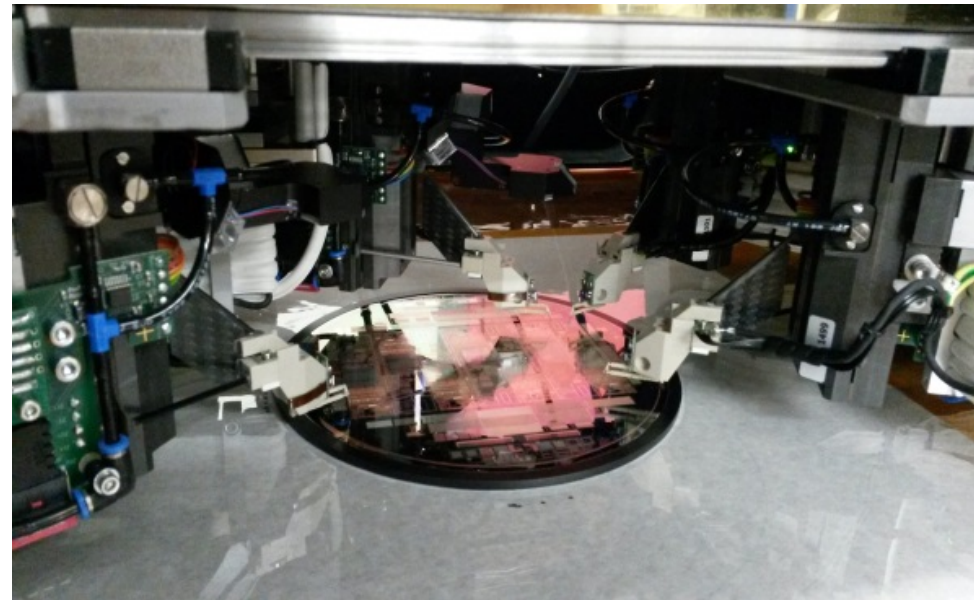
- Test vehicle for assembly and electrical performance test

Sensor chips are being produced... in the meanwhile ... Electrical Multi Chip Module optimizations



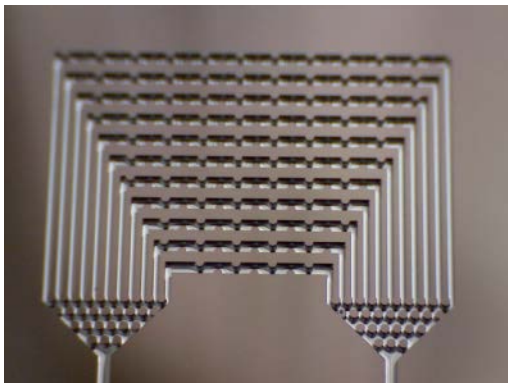
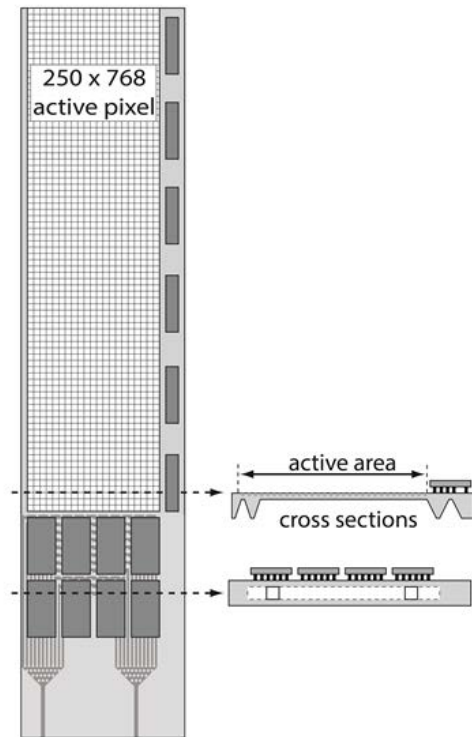
Good die test

- Sophisticated flying needle testing with  $O(130k)$  touchdowns in periphery

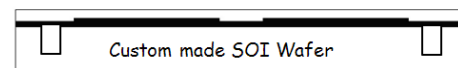
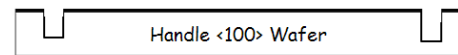


All silicon modules developed for BELLE II vertex detector can be seen as prototype modules for detectors at future Linear colliders

# ● Future all silicon modules - Integrated micro-channels



a) oxidation and back side implant of top wafer



b) wafer bonding and grinding/polishing of top wafer

c) process → passivation

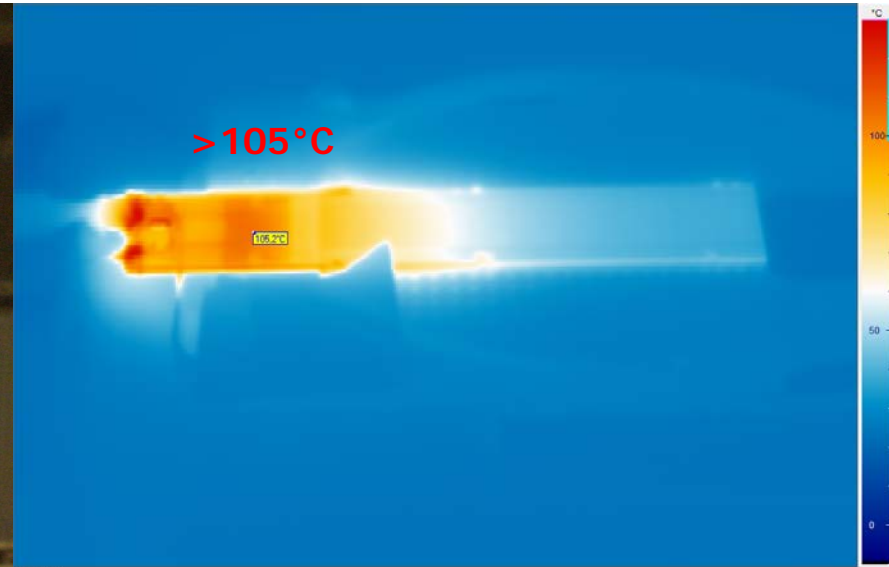
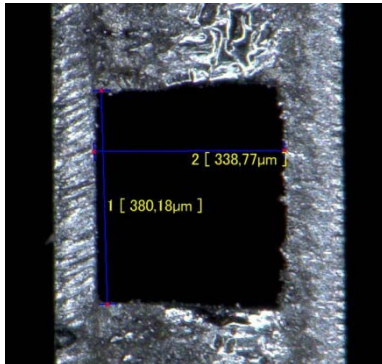


d) anisotropic deep etching opens "windows" in handle wafer

## The SOI approach: thinned all-silicon module with integ. cooling

- most heat generated by read-out ASICs
- idea: integrate channels into handle wafer beneath the ASICs
- make use of the thick handle wafer at the end-of-module
- channels etched before wafer bonding → cavity SOI (C-SOI)
- full processing on C-SOI, thinning of sensitive area
- micro-channels accessible only after cutting (laser)

- Future all silicon modules / First prototypes for thermal studies

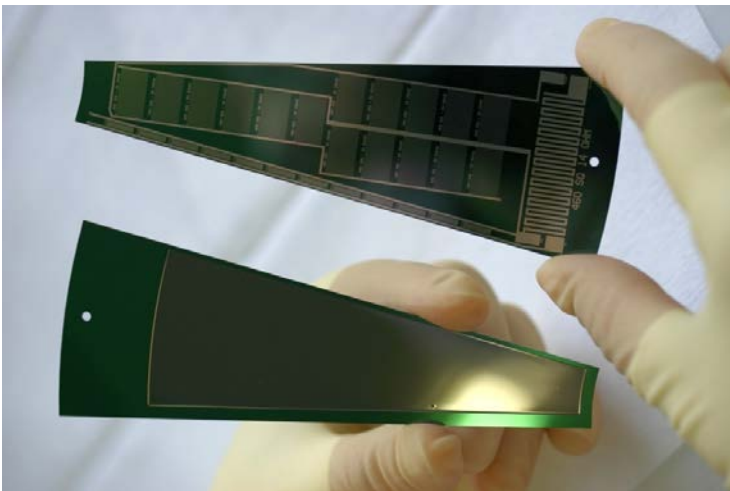
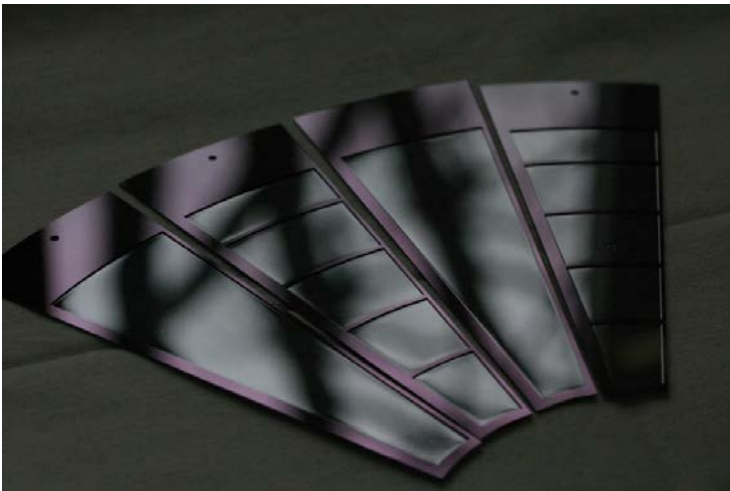


Collaborative work with: University of Bonn and IFIC



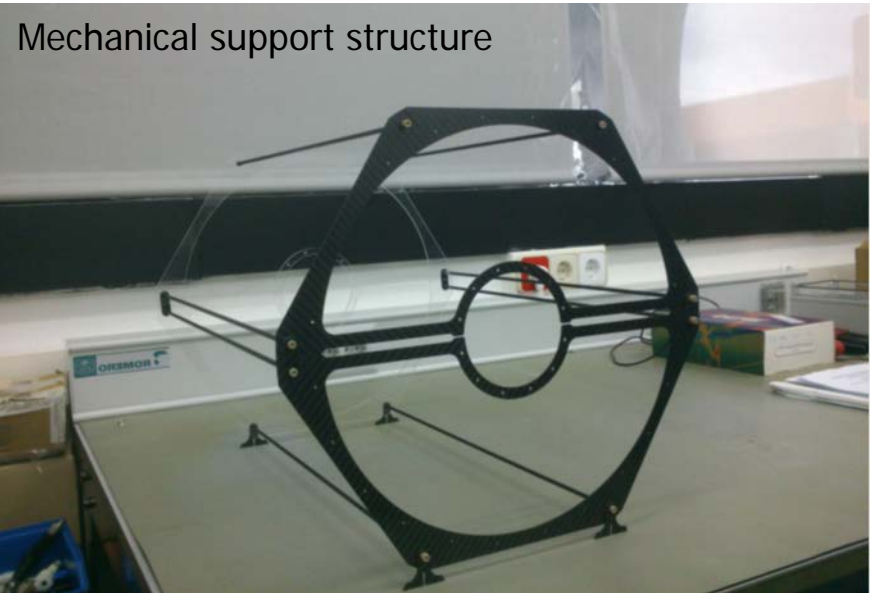
● Future all silicon modules - Forward tracking disks in ILD

Thermo mechanical Si modules



**FTD pixel disk mock up**

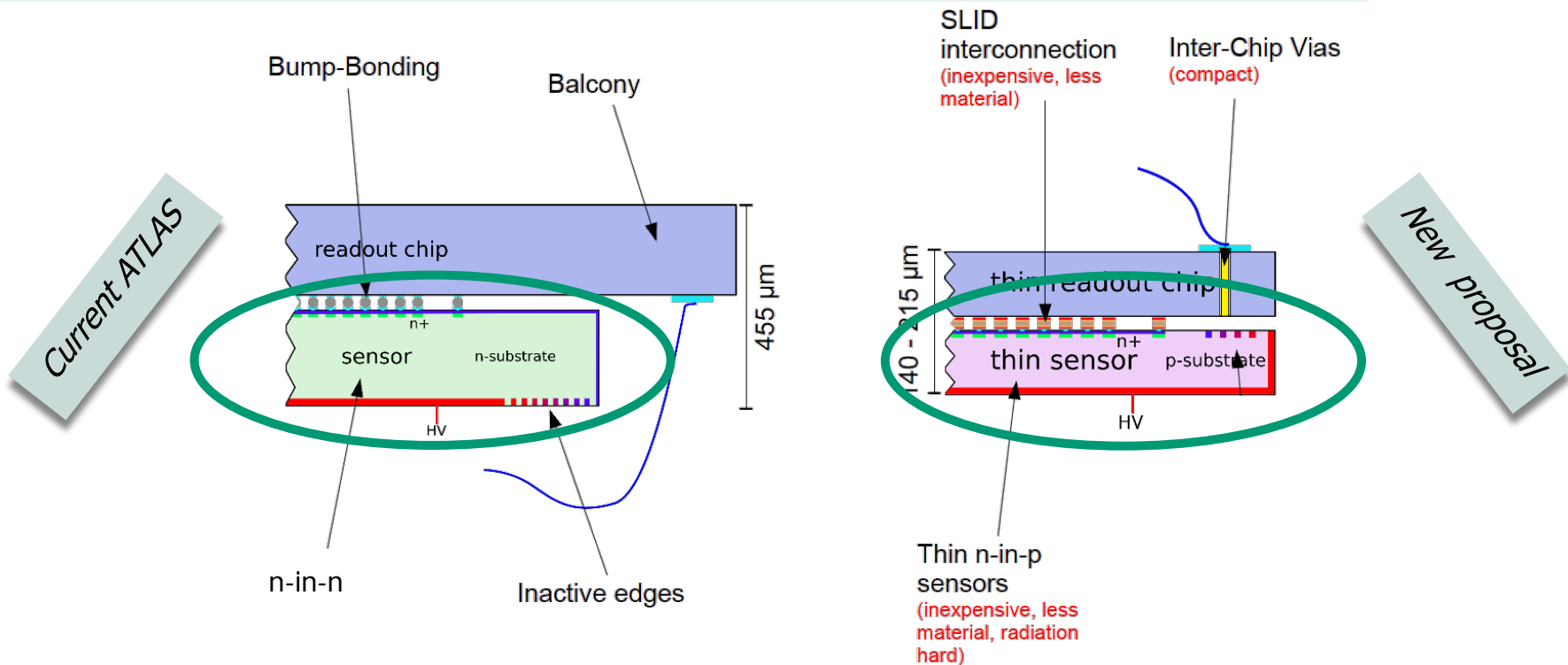
- DEPFET mechanical petals
  - 75  $\mu\text{m}$  Silicon ( $<0.2\% X_0$ )
- Support disk
  - 1mm ( $0.09\% X_0$  avg. area)
- CF connection tubes



Collaborative work with: University of Bonn and IFIC Valencia



# ● The ATLAS Pixel Detector Upgrade – HLL involvement

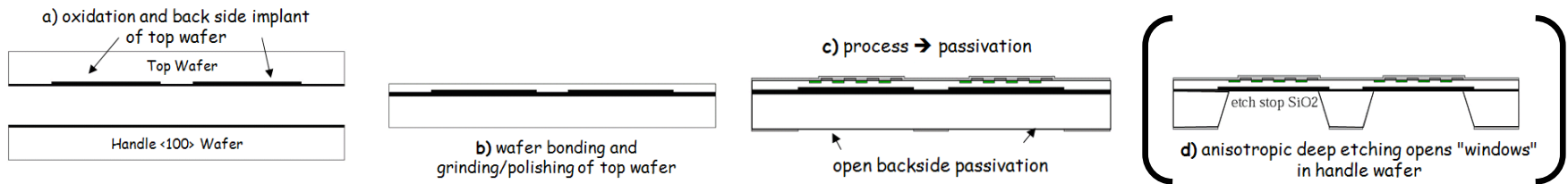


## Objectives of the project

- Design and build thin pixel sensors on p-type FZ material
- Show compatibility and radiation hardness of sensors with SLID metal system
- Show feasibility of the post-processing of existing r/o electronics (ICV and thinning)
- Build demonstrator module with thin sensors, using SLID and ICV through the r/o Chip

(collaboration partner MP Physics)

# ● Thin pixel Sensors @ MPG HLL

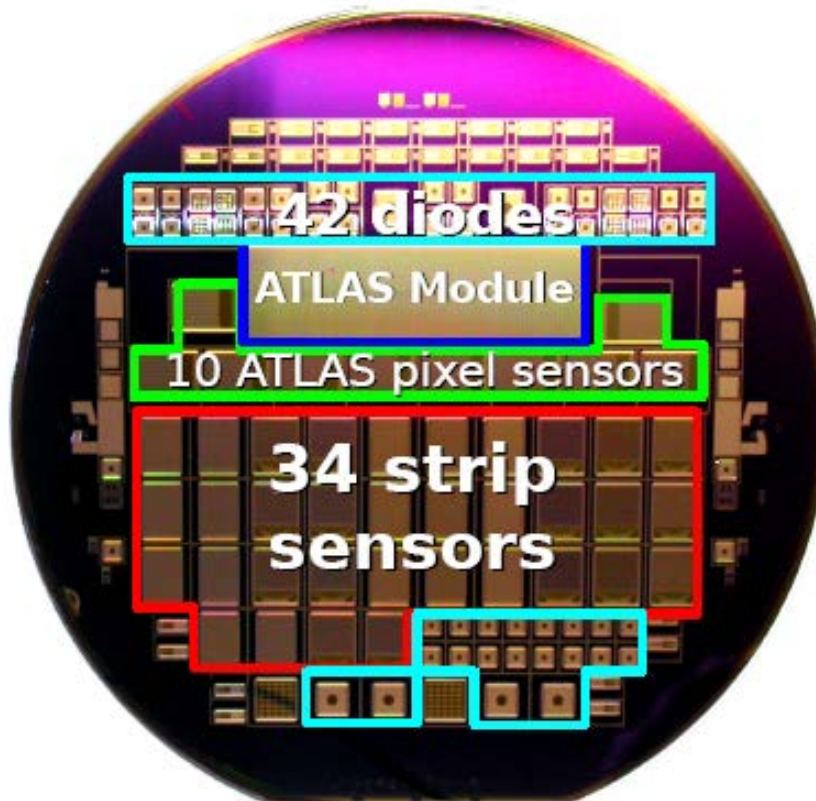


## Advantages of thin sensors:

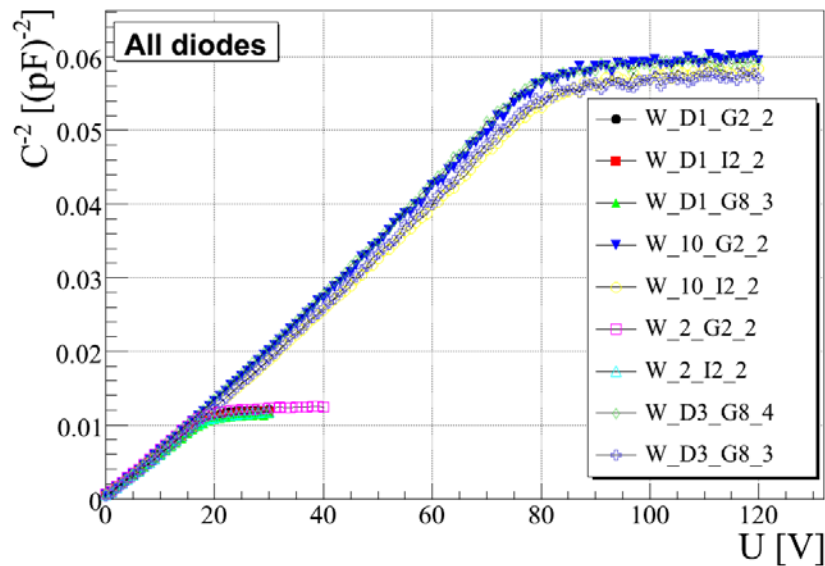
- Lower leakage currents:  $I \sim V$
- Lower full depletion voltage:  $V_{fd} \sim t^2$
- Potentially better radiation tolerance
- ... less material

## Thin sensor production at MPG HLL:

- n-in-p wafers & n-in-n wafers
- $t = 75 \mu\text{m}$  and  $150 \mu\text{m}$
- Diodes: technology monitoring
- Pixel sensors: prototype modules
- Strip sensors: charge measurements

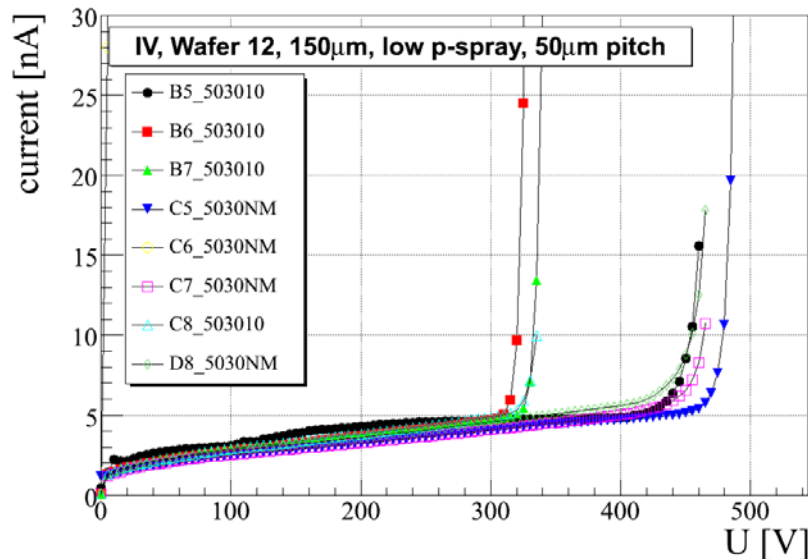


# ● Thin pixel Sensors – Test Results



## Capacitance characteristics (Diodes)

- 150  $\mu\text{m}$  thin sensors:  $V_{fd} \sim 80\text{V}$ .
- 75  $\mu\text{m}$  thin sensors:  $V_{fd} \sim 20\text{V}$ .
- Scaling  $d^2 \sim V_{fd}$  nicely visible.



## IV Pixel and mini strip sensors:

- Break down voltage much higher than depletion voltage.
- Low currents before irradiation ( $< 5\text{nA}/\text{cm}^2$ ).
- also after irradi. (up to  $10^{16} \text{ n}_{eq}/\text{cm}^2$ ) very good break down behavior, IV, CCE

# ● X-ray fluorescence spectroscopy: MIXS on BepiColombo

## *MIXS - First Imaging X-ray spectrometer for planetary X-ray fluorescence*

- is the first planetary XRF instrument using a high performance **imaging optics**, not just a collimator.  
Much better spatial resolution!  
Look inside craters, identify more features!
- is the first planetary XRF instrument using an **energy dispersive solid-state detector** with excellent energy resolution and low energy threshold.  
Allows to observe the important lines of Iron, Silicon, Magnesium etc. directly!

(collaboration partner MP Solar System Research)

### DEPFET Macropixel Matrix

#### ▷ Format

- ▶ **1.92 x 1.92 cm<sup>2</sup>**
- ▶ **64 x 64 pixels**
- ▶ **300 x 300 μm<sup>2</sup> pixel size**

#### ▷ Energy resolution

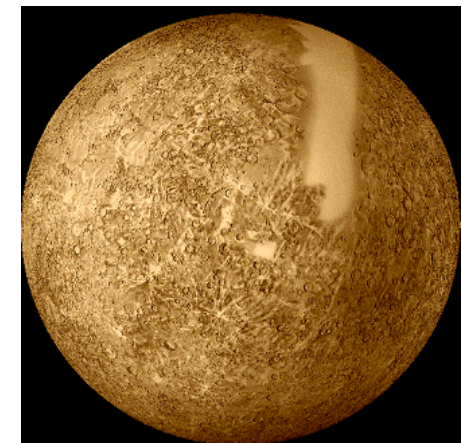
- ▶ **200 eV FWHM @ 1 keV**
- ▶ QE > of 80 % @ 500 eV

#### ▷ Time resolution

- ▶ **< 1 ms** due to dynamics

#### ▷ Radiation hardness

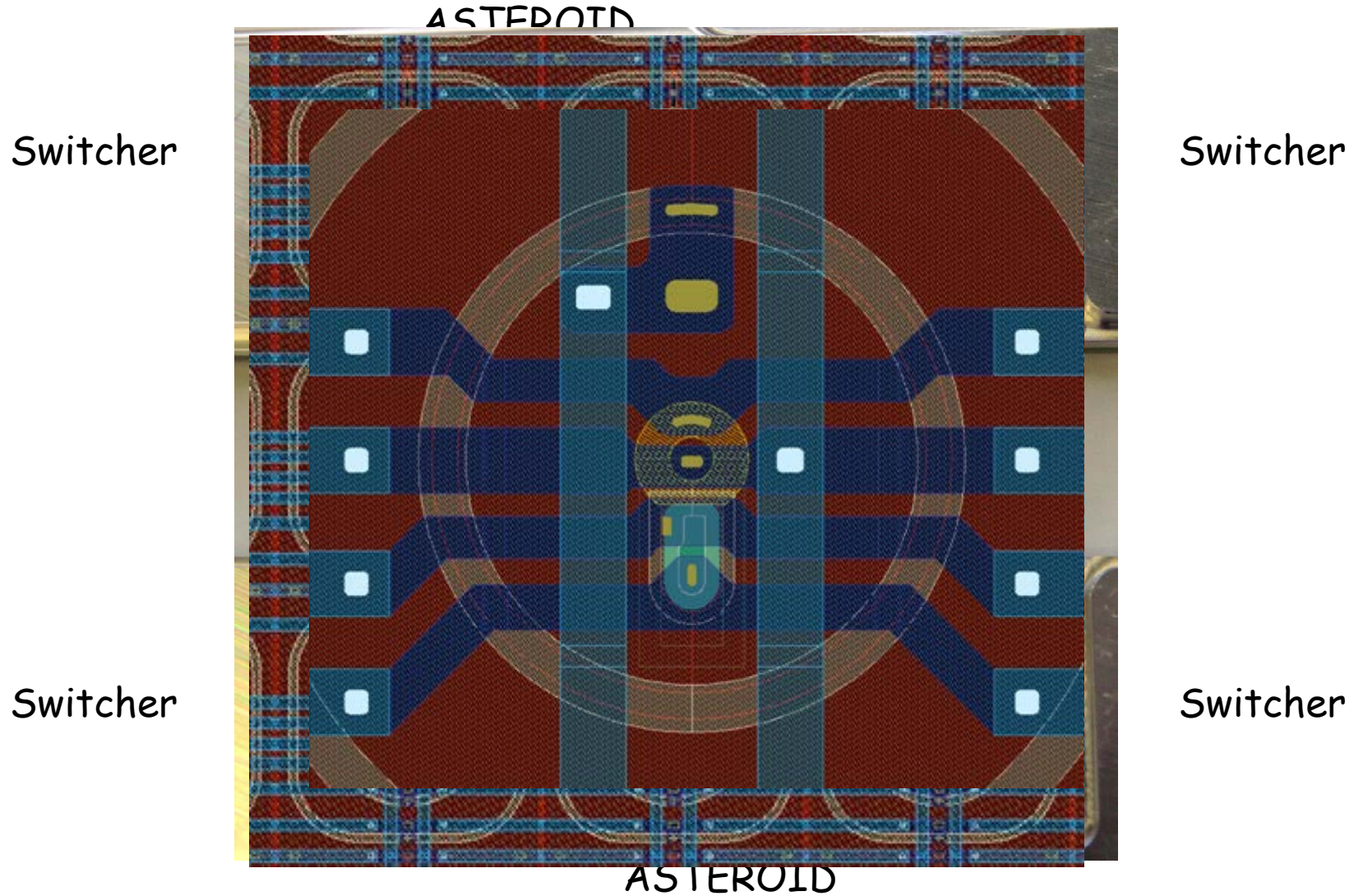
- ▶ ~ 20 krad ionizing
- ▶  $3 \times 10^{10}$  10 MeV p/cm<sup>2</sup>
- ▶ **equivalent to**  $1.11 \times 10^{11}$  1 MeV n/cm<sup>2</sup>



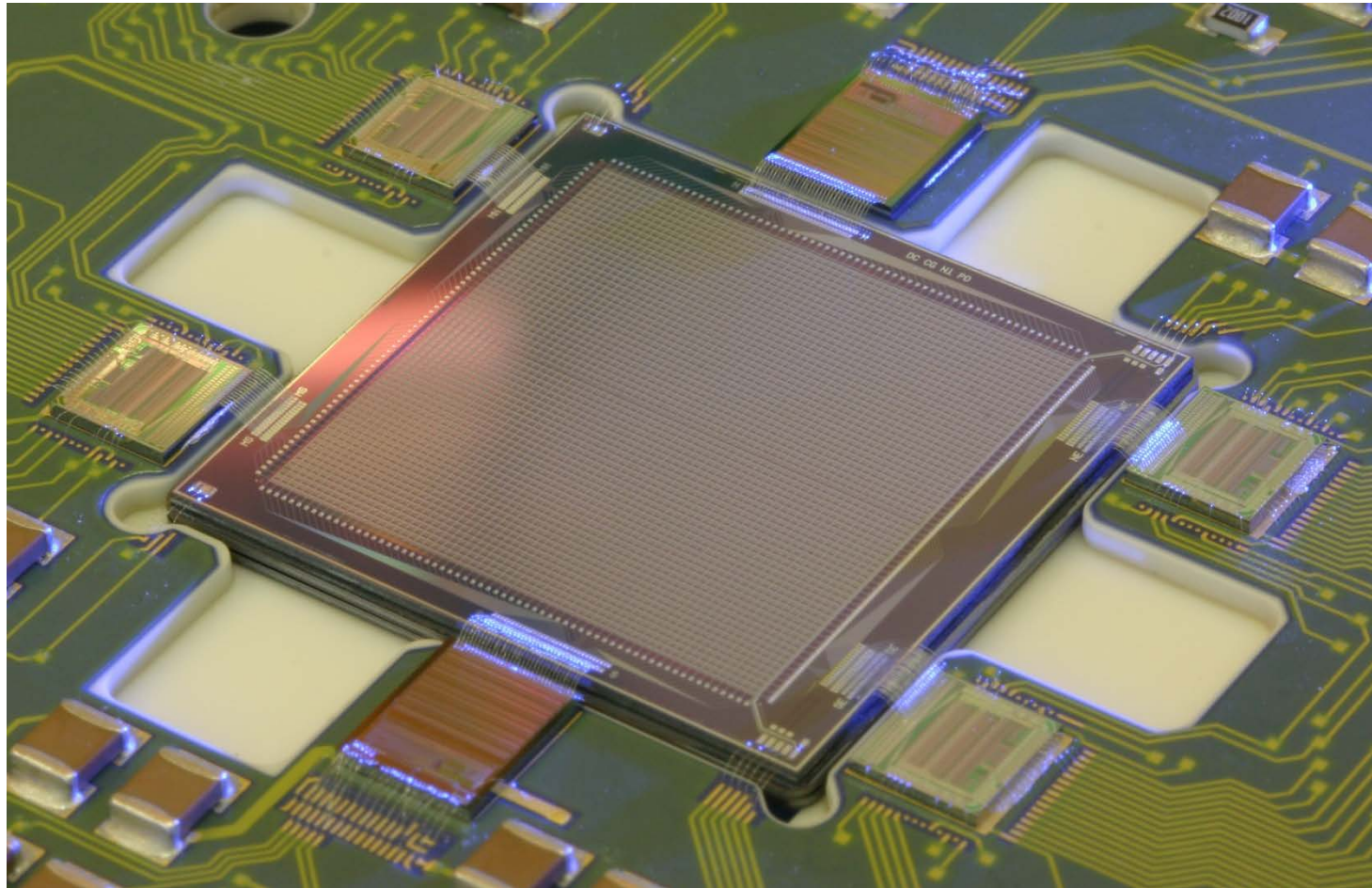
Mercury surface as seen by Mariner 10



- Detector overview

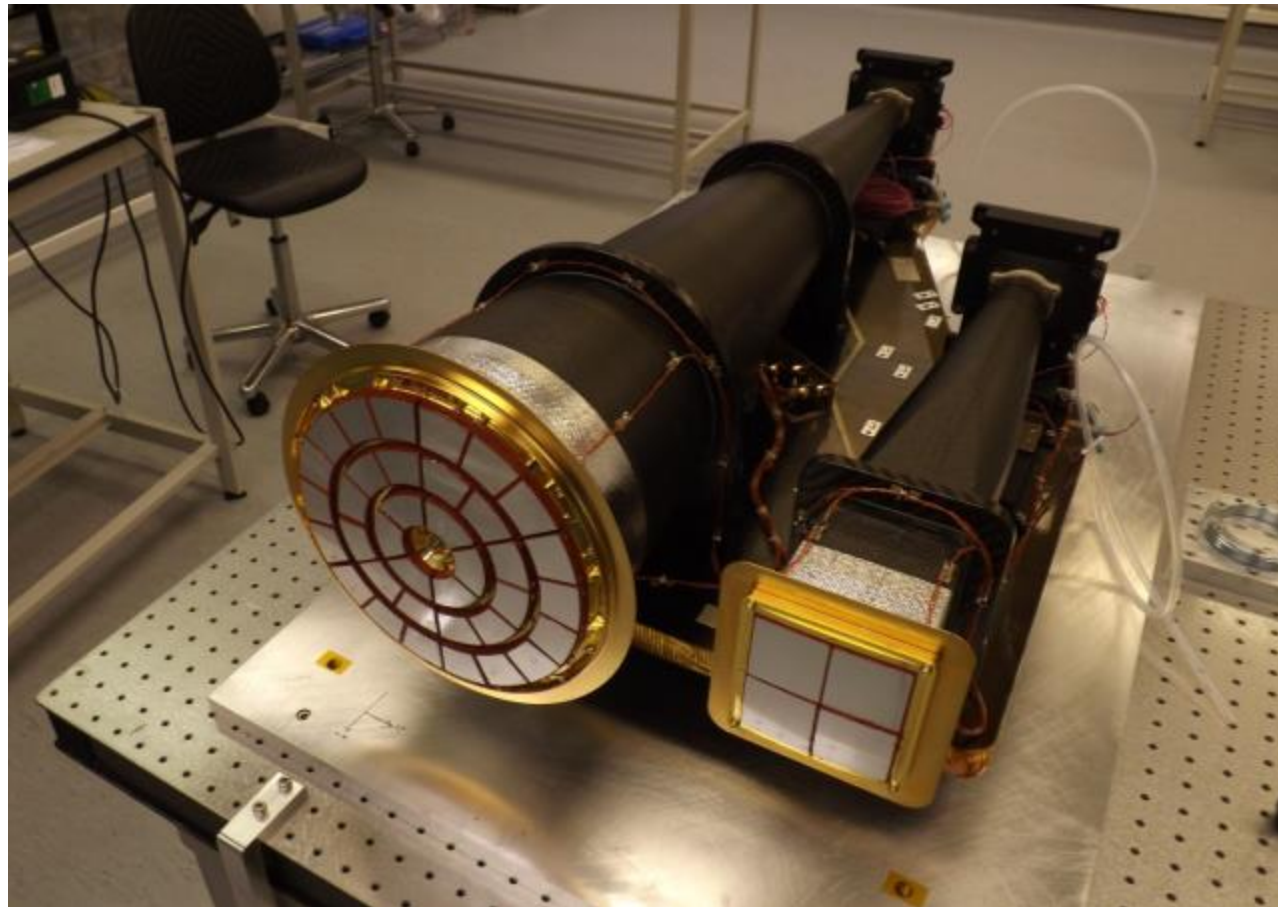


- MIXS hybrid

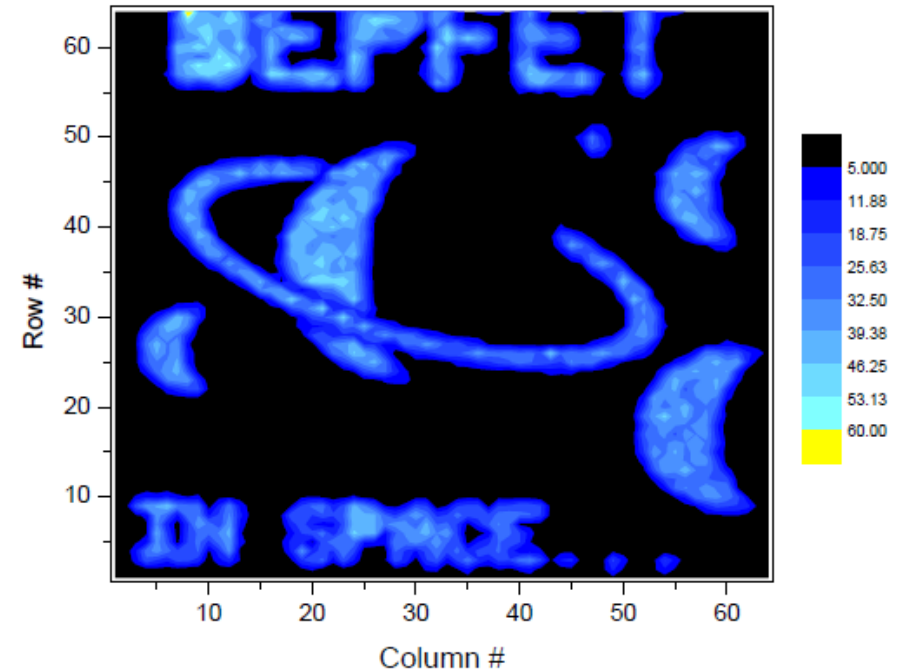




- Fully assembled Qualification Model



## ● Measurements



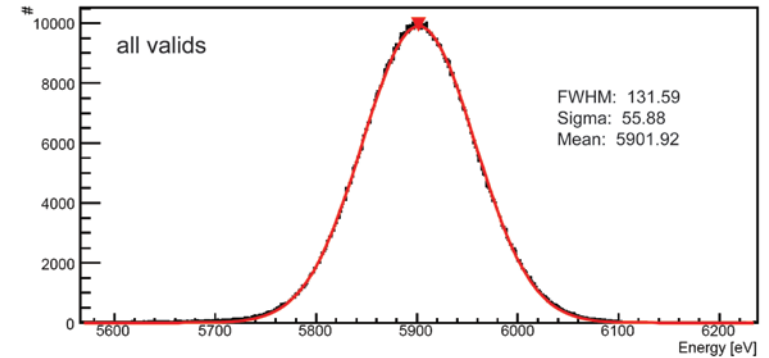
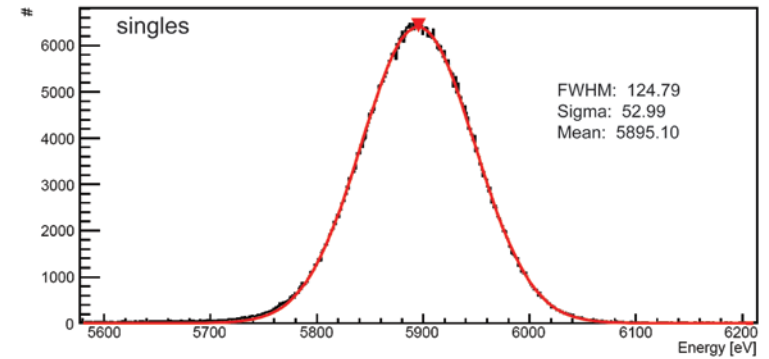
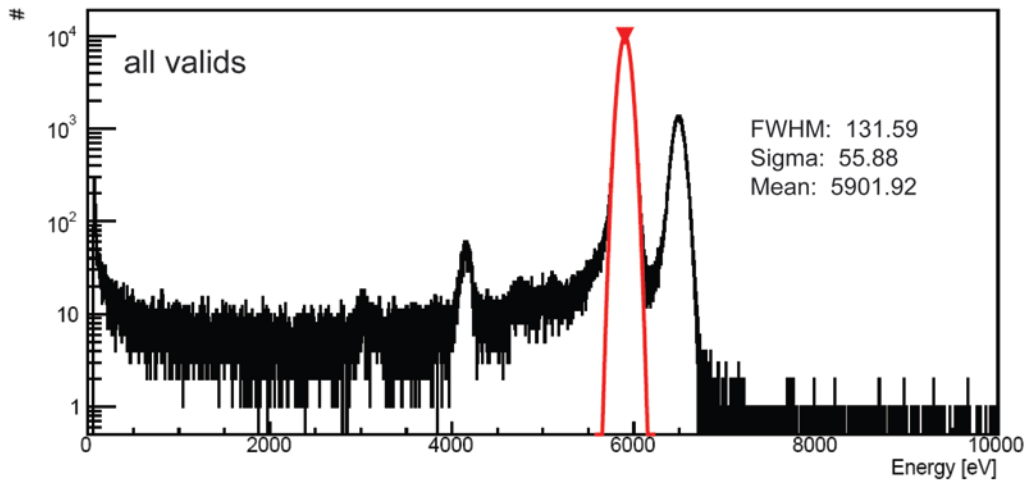
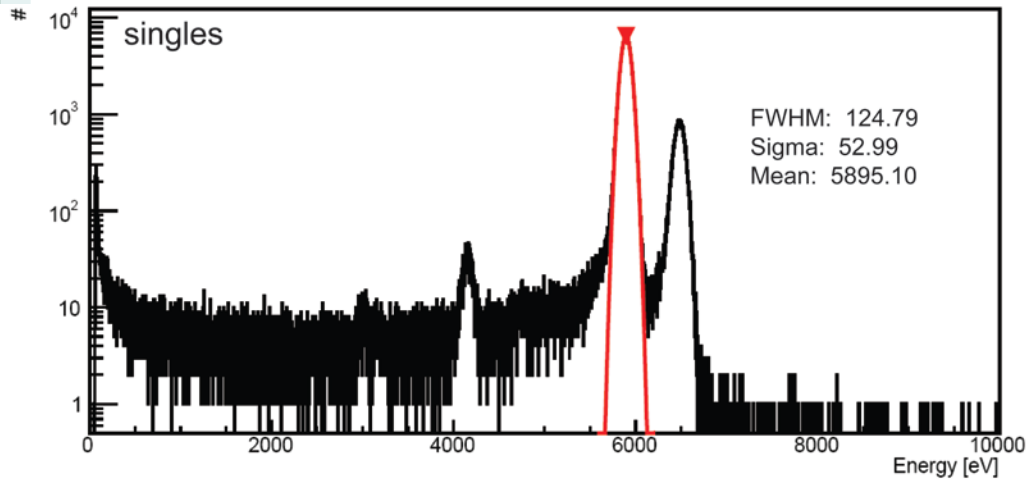
### ■ Operating conditions

- ✦  $-40\text{ }^{\circ}\text{C}$
- ✦  $T_{\text{row}} = 5.2\text{ }\mu\text{s}$
- ✦  $T_{\text{frame}} = 167\text{ }\mu\text{s} / \text{frame}$
- ✦ Framerate  $\sim 6\text{ kfps}$
- ✦  $I_{\text{pixel}} = 125\text{ }\mu\text{A}$

Shadow image of a  $450\text{ }\mu\text{m}$  thick silicon baffle with an  $^{55}\text{Fe}$  source mounted directly in front of the sensor



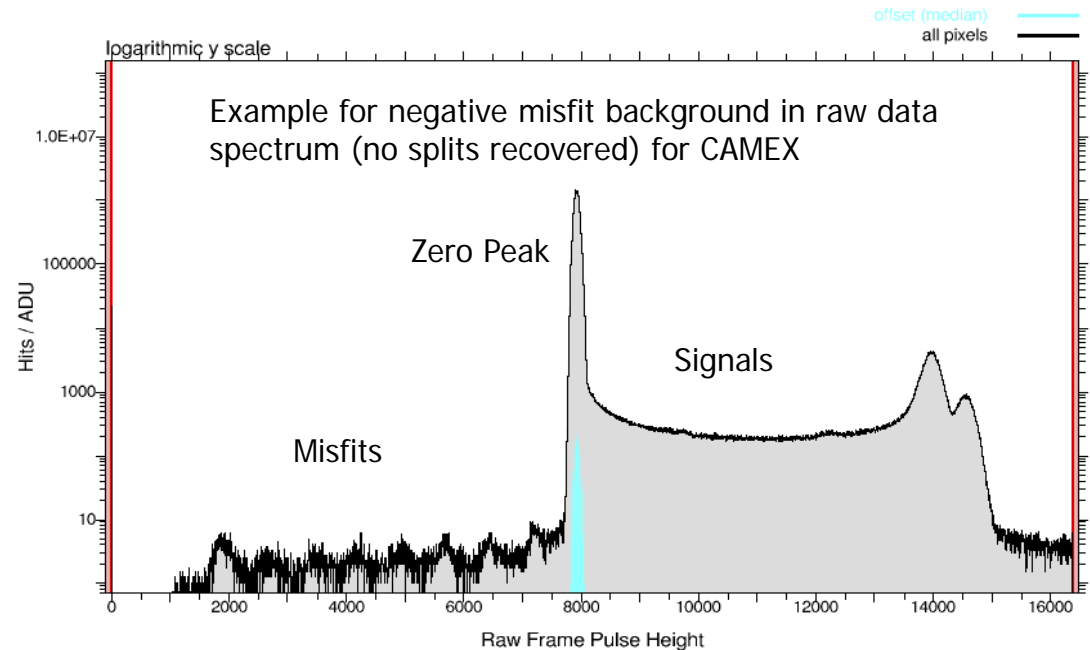
# ● Spectral performance



- $^{55}\text{Fe}$  source
- singles: FWHM = 124.8 eV @ 5.9keV
- $T \sim -85^\circ\text{C}$
- 415  $\mu\text{s}/\text{frame}$

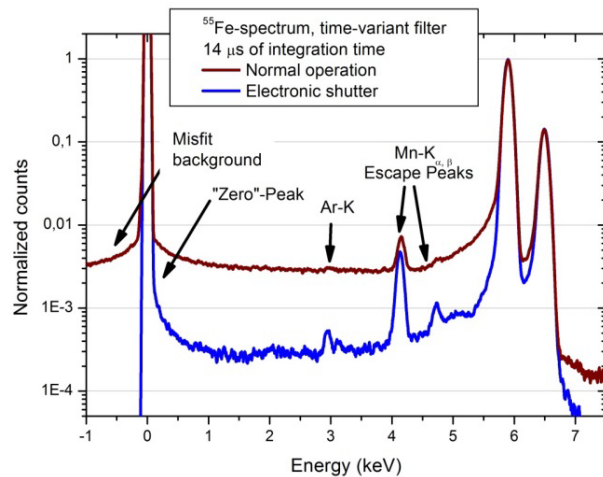
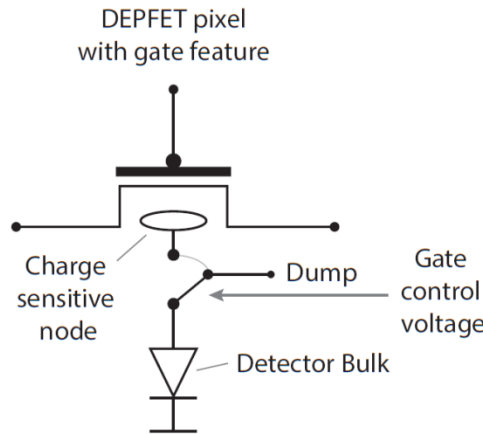
# Misfits

- Events arriving during signal processing time cause “negative” and “positive” background in signal (Misfits)
  - Negative signals are easy to be tagged
  - Positive signals cause irreducible background
  - Spectral shape corresponds to the negative misfit background mirrored at the zero peak
- 
- Fraction of misfits only depends on ratio between readout time and integration time
  - Worse for higher degree of parallelization
  - Worst case is fully parallel readout (hybrid pixel sensor)
  - How to avoid?



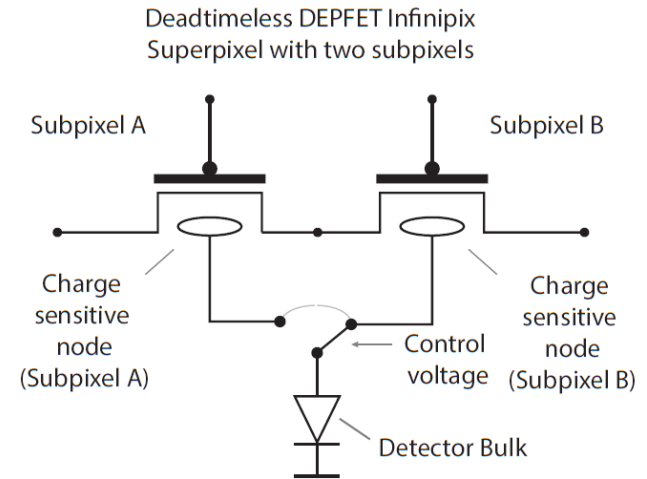
# Solutions for Misfits

## Gated PIX (GPIX)



- Very effective!
- **Drawback: Deadtime!**

## InfiniPIX



- Superpixel composed of two subpixels
- One subpixel is sensitive. i.e. collects charge from bulk
- The second one is insensitive, i.e. keeps charge already collected, but no new charge will be added, as it is collected by sensitive subpixel
- Only insensitive pixel can be read out
- Shielding is achieved by deviating potentials
- Most simple solution: switching the drain potentials of subpixels

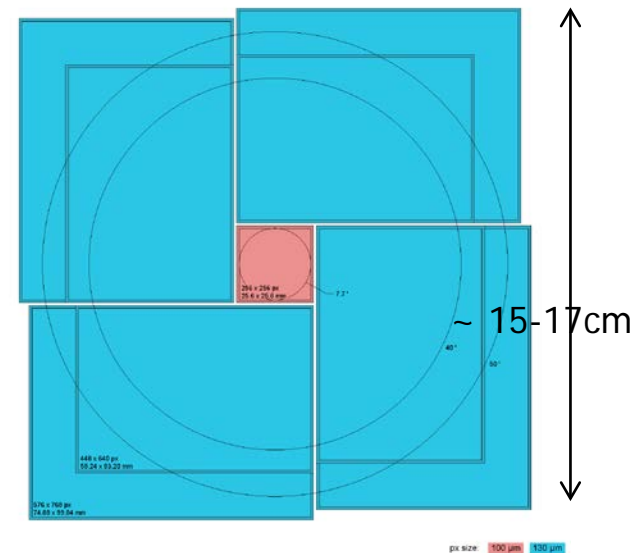
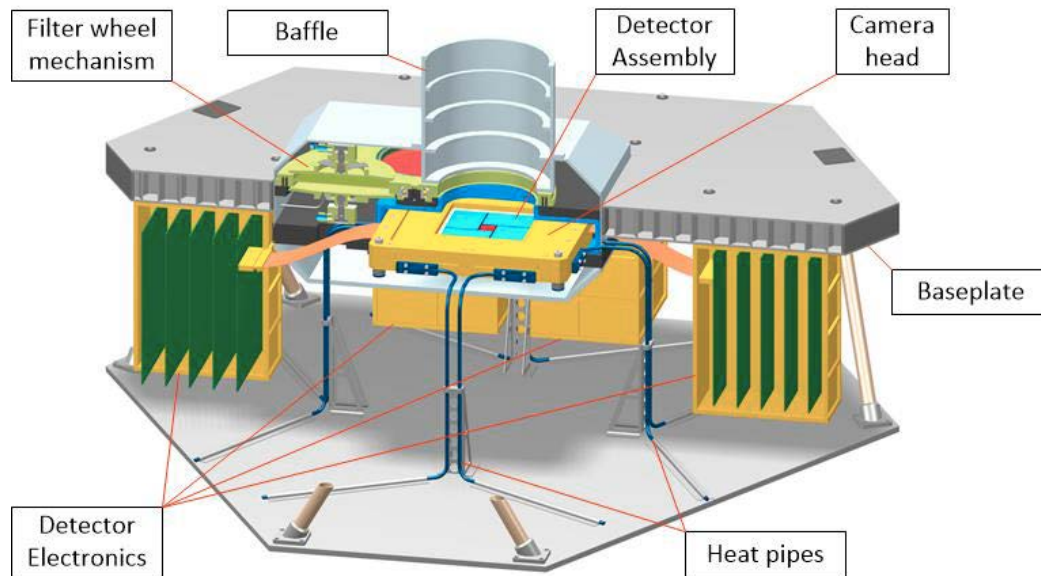
# ATHENA mission – Wide Field Imager (WFI)

Athena (the Advanced Telescope for High-Energy Astrophysics), has been proposed as ESA's next-generation X-ray astronomy observatory (Launch slot 2028).

(collaboration partner  
MP Extraterrestrial Physics)

To address two key questions in modern astrophysics:

- How does ordinary matter form the large-scale structures that we see today?
- How do black holes grow and shape the Universe?

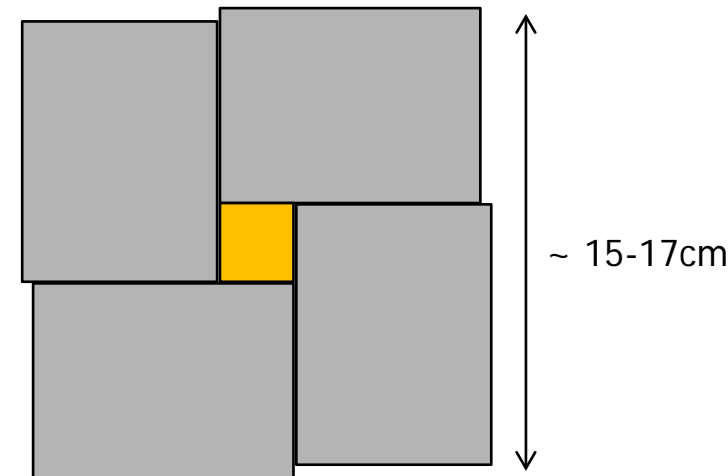
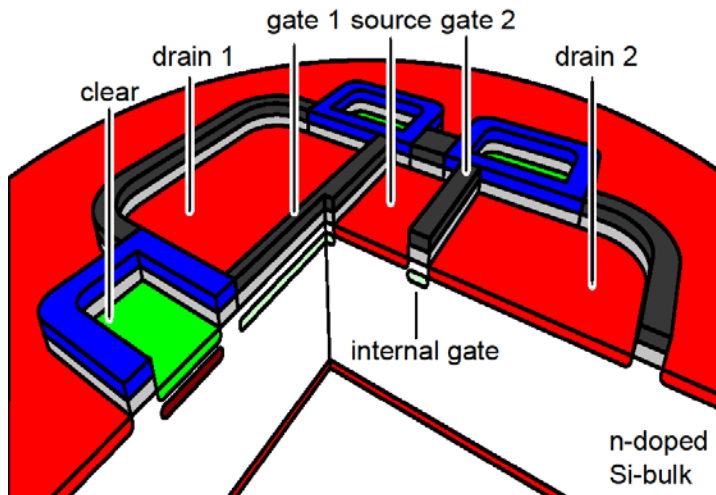




- ATHENA mission – Wide Field Imager (WFI)

Central chip: fast timing and high count rate capability

Idea: use infinipix like DEPFET matrix



### First prototypes Infinipix DEPFET

- > shutter speed < 200ns
- > charge suppression <  $5 \cdot 10^{-4}$
- > charge handling  $\approx 23500e$  ( $\approx 85keV$ )

# ● Requirements for the XFEL detectors

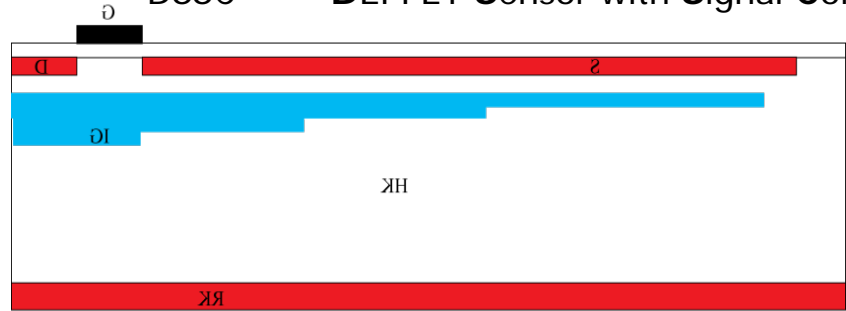


## Integrating Area Detector

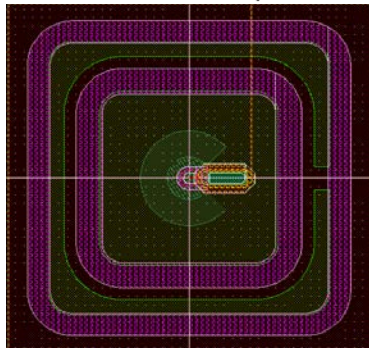
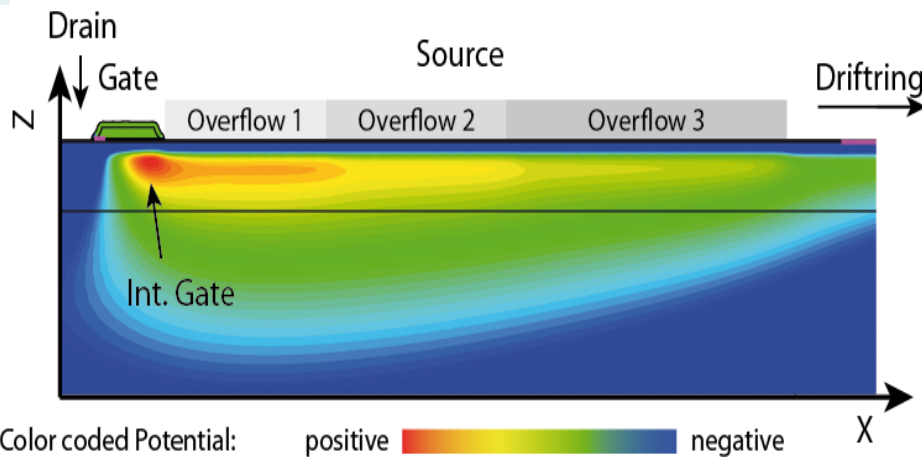
	XFEL (e.g. XPCS)	DEPFET array system
single photon resolution	yes	yes
energy range	$0.5 < E < 24$ (keV)	$0.5 < E < 25$ [keV]
ang. resolution or pixel size	4 $\mu$ rad	200 $\mu$ m
sig.rate/pixel/bunch	$10^3$	$10^3@10$ KeV
quantum efficiency	> 0.8	> 0.8 from 0.3 to 12 keV
number of pixels	512 x 512 (min.)	1024 x 1024
frame rate/repetition rate	10 Hz	yes, triggerable
<b>XFEL burst mode</b>	<b>5 MHz (3.000 bunches)</b>	<b>4.5 MHz</b>
Readout noise	< 150 e <sup>-</sup> (rms)	< 50 e <sup>-</sup> (rms)
cooling	possible	- 20° C optimum, room temperature possible
vacuum compatibility	yes	yes
preprocessing	no (yes) ?	possible upon request
4-side buttability	yes	yes

# ● Detector Concept – DEPFET with signal compression

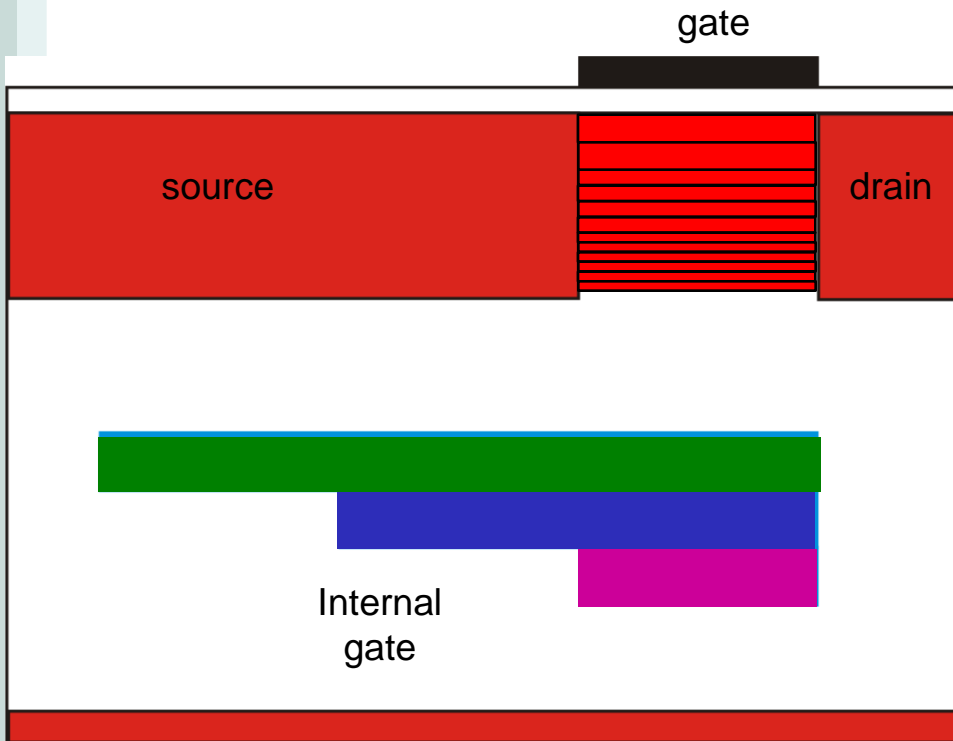
DSSC - DEPFET Sensor with Signal Compression



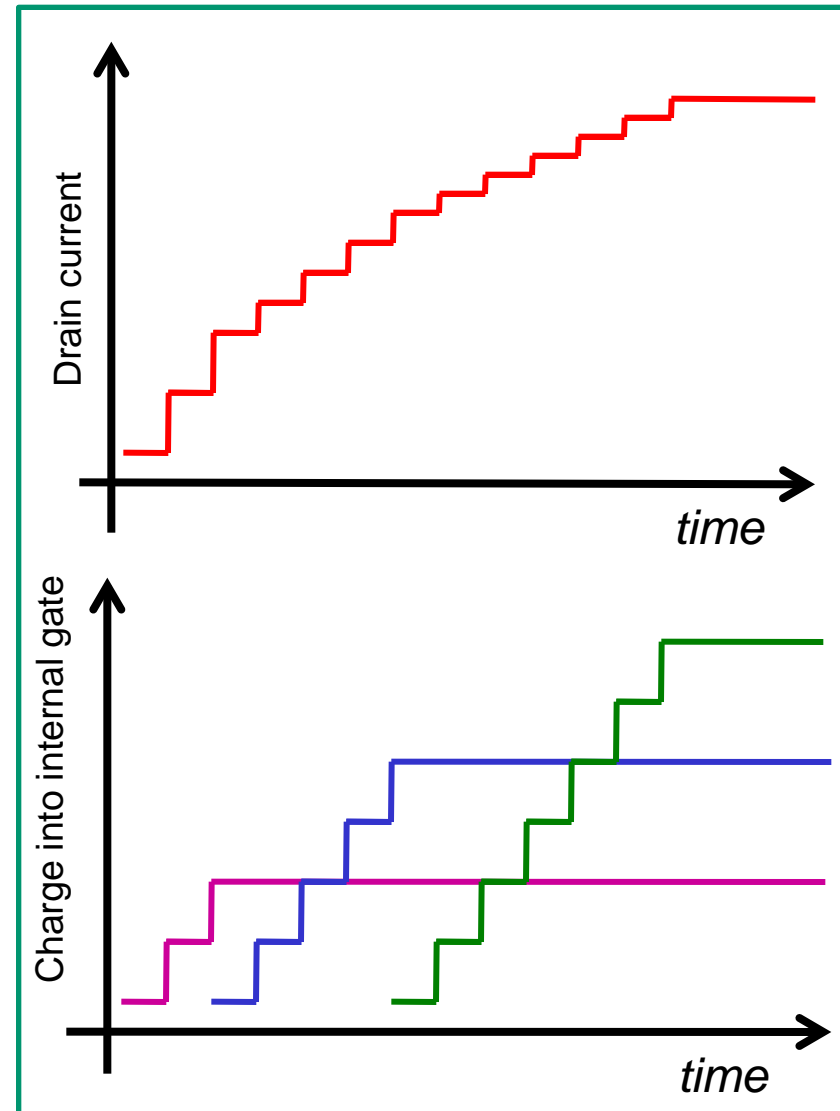
- The internal gate extends into the region below the source
- Small signals assemble below the channel, being fully effective in steering the transistor current
- Large signals spill over into the region below the source. They are less effective in steering the transistor current.
- 200 x 200  $\mu\text{m}$  pixel has been designed and produced



# ● Detector Concept – Working principle



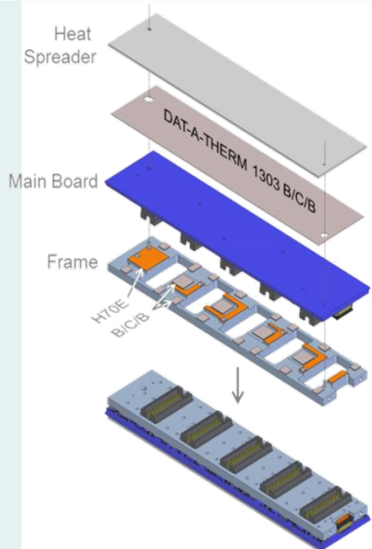
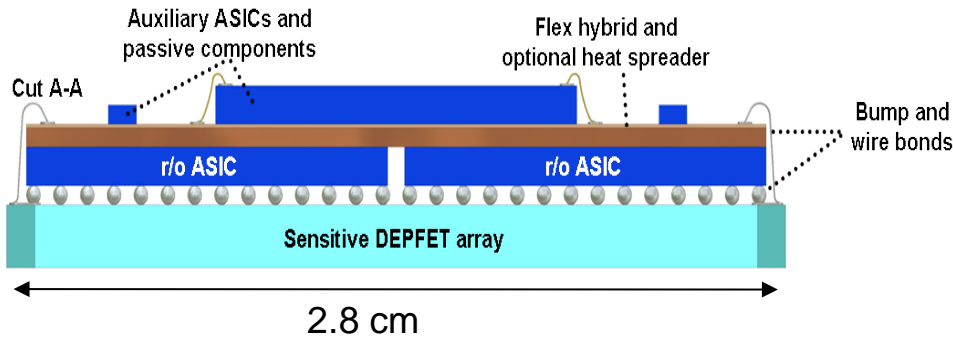
- A constant charge is injected at fixed time intervals and the internal gate regions are progressively filled
- In the experiment the charge is deposited at once but the DEP-FET response is the same



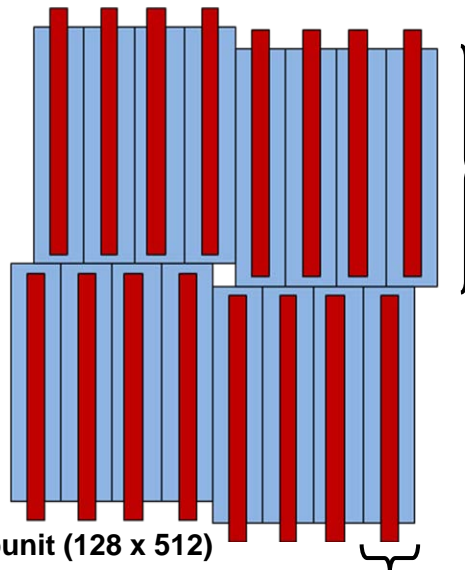


# Focal Plane

## Submodule 128x512



21 cm



**detector module (512 x 512)**

**Monolithic detector subunit (128 x 512)**

## Multi Chip Modules

- ▷ DEPFET Sensor bump bonded to Readout ASICs
- ▷ Optional Heat spreader
- ▷ Flex Hybrid with passive components and auxiliary ASICs (e.g. voltage regulators)
- ▷ Sensor (512x128 pixels) 2.56x10.24 cm<sup>2</sup>
- ▷ 16 readout ASICs (64x64)
- ▷ Dead area: 10-15%

Sensor development by MPG HLL  
System development by DSSC collaboration

# ● DSSC interconnection and assembly

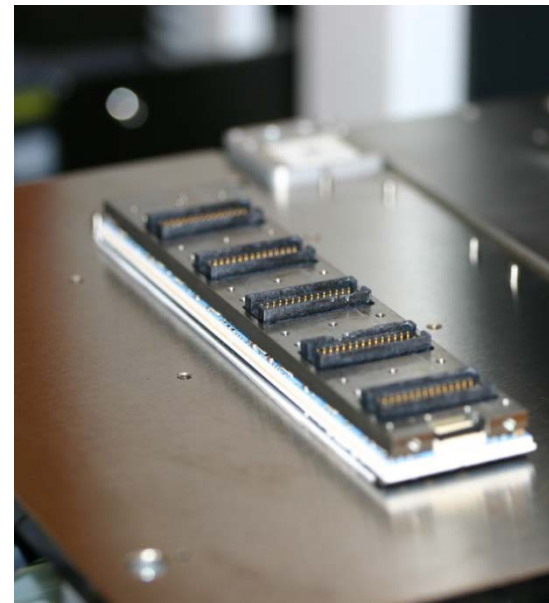
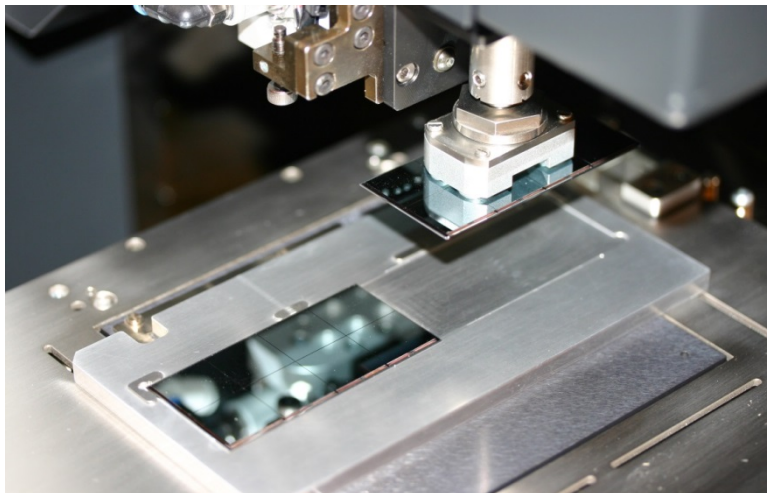
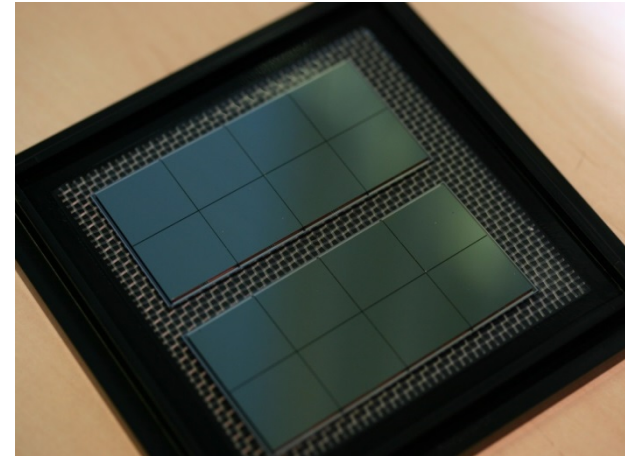
## In House Flip chip

Fully automated flip-chipping

Reproducible yield :

~100% (1-3 missing bonds out of ~33000)

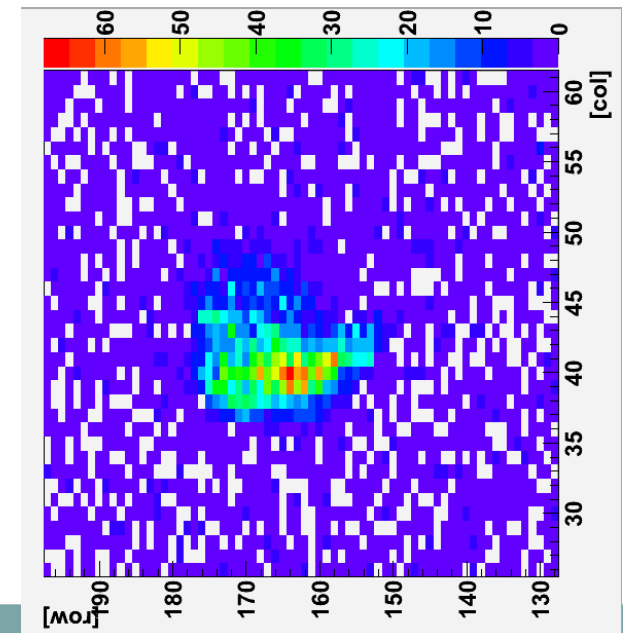
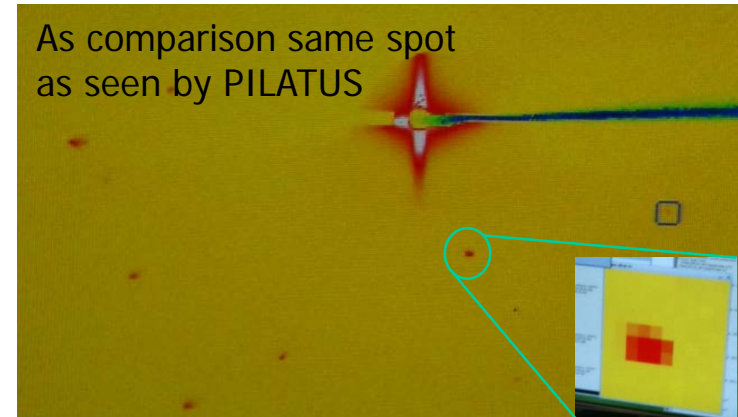
## Macro-assembly equipment installed



# ● BELLE & ILC DEPFETs for Photon Science

First tests: slow readout system 2.3ms frame readout time (signal integration time) with about 150Hz DAQ readout rate (one frame is read out every 6ms)

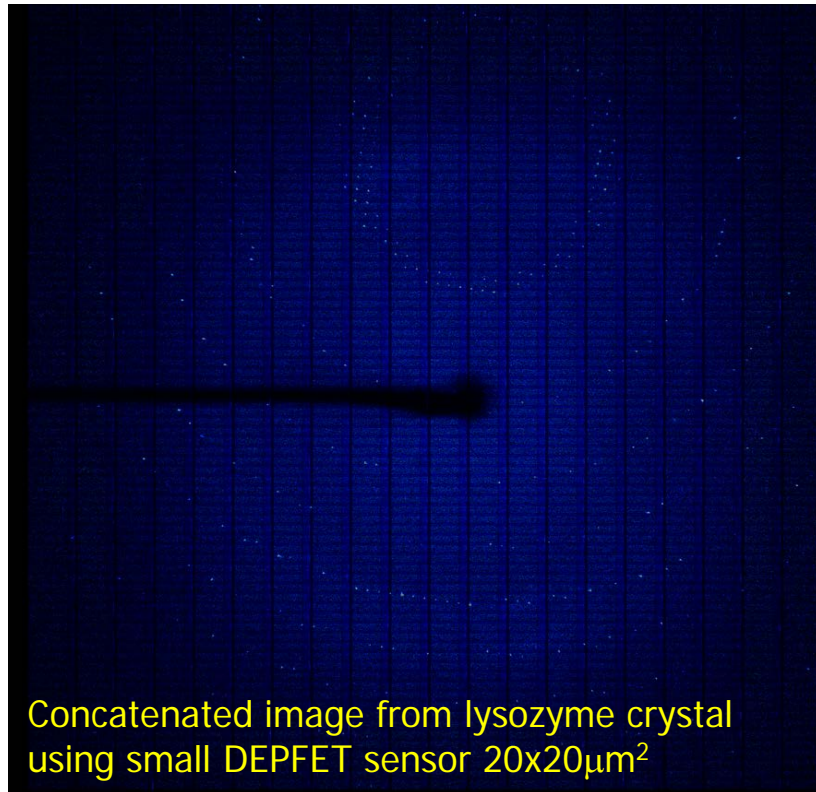
Matrix – ILC type 24x32 $\mu\text{m}^2$  pixel 450 $\mu\text{m}$  thick  
5120 $\mu\text{m}$  x 1280 $\mu\text{m}$  (256 x 64 pixels)



Lysozyme crystal – position of diffraction spots defined by PILATUS and then DEPFET matrix driven to that point



● BELLE & ILC DEPFETs for Photon Science



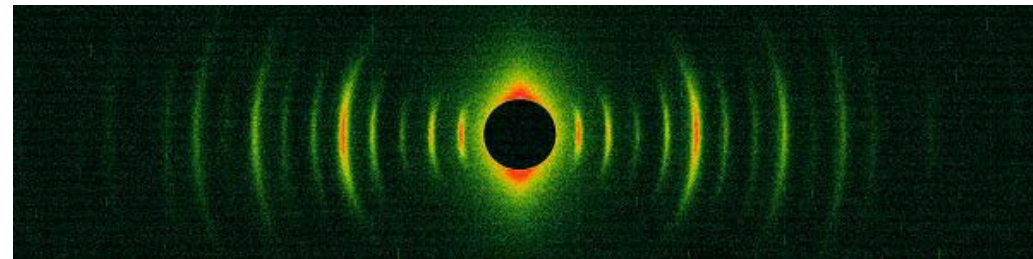
**X-ray Diffraction Image  
from the Protein Crystal**

X-ray energy 12.4 keV  
(wavelength=1.0Å)  
@ BL-5A

Concatenated image from lysozyme crystal  
using small DEPFET sensor 20x20μm<sup>2</sup>

Collagen from Chicken Achilles tendon  
o X-ray energy 8.33 keV (wave length=1.488Å)  
@ BL-10C  
o 1-dimentional orientation  
o Lattice spacing: d=653Å

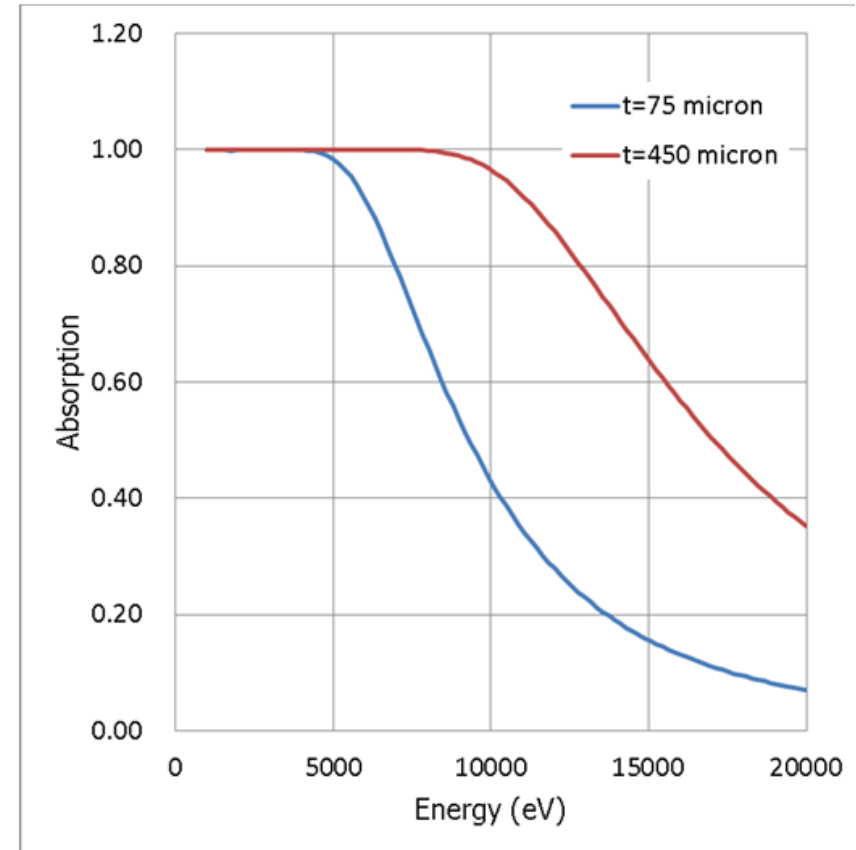
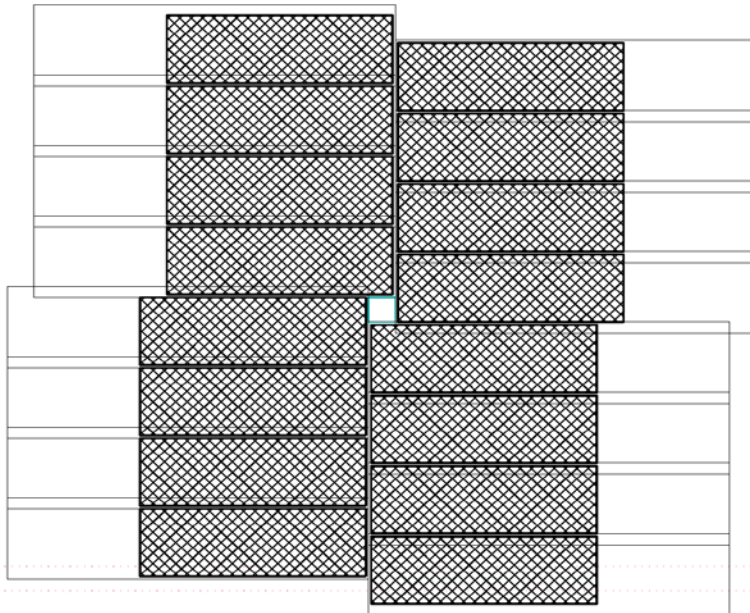
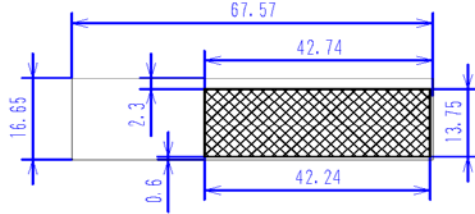
**X-ray solution scattering image**





● BELLE like sensors (20μs) for PF KEK

pixel size: 55 μm x 55 μm  
 number of rows and columns: 250 x 768

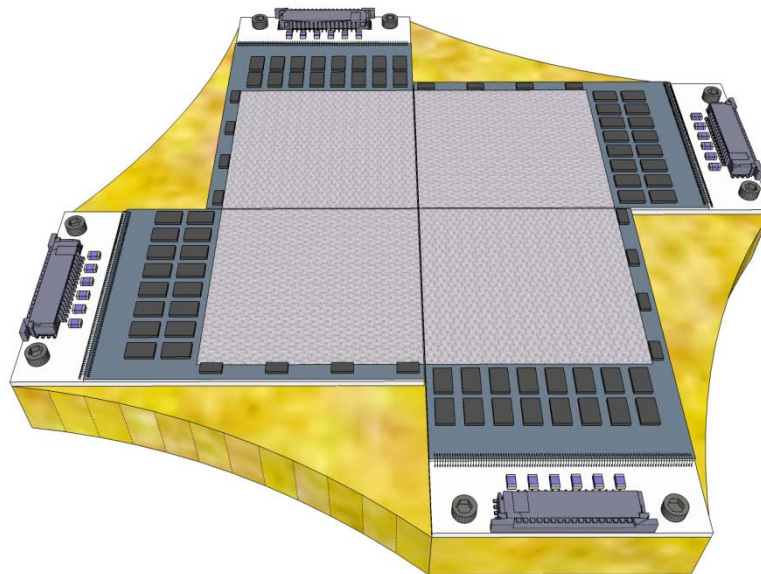
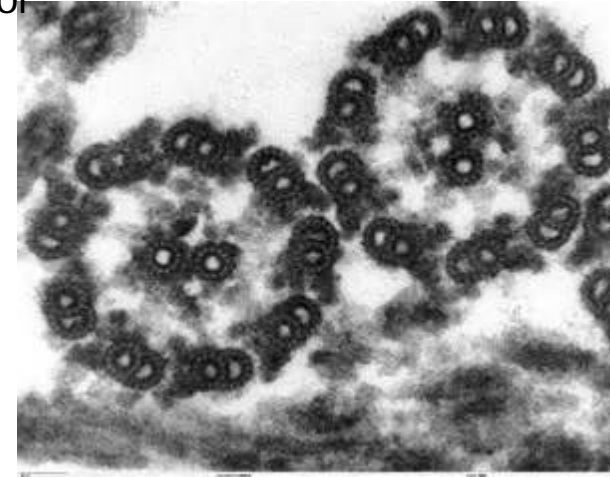


- DEPFETs for low E electron detectors

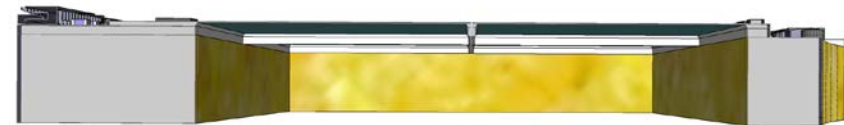
**Goal:** develop high speed direct hit low energy electron detector

**Solution:** thin, nonlinear DEPFETs with 80kHz frame rate

- 1Mpix, 60 $\mu$ m DEPFET pixel, 4 quadrants, 6x6 cm<sup>2</sup> sensitive
- 50 $\mu$ m thin sensitive area
- Bidirectional 4-fold read out, frame rate: 80kHz
- memory to store ~100 frames

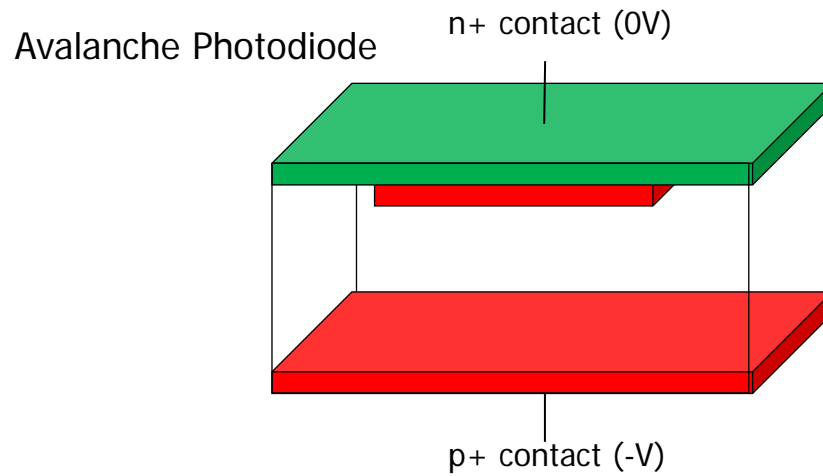


(collaboration partner MP Structural Dynamics)

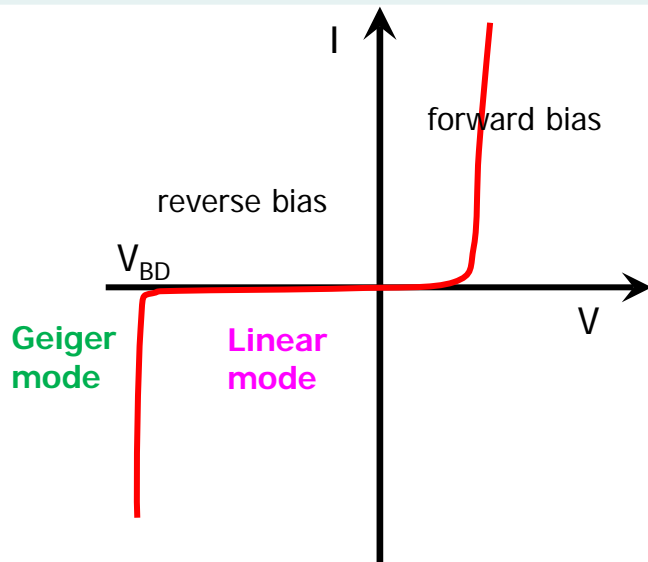


- SNR improvements

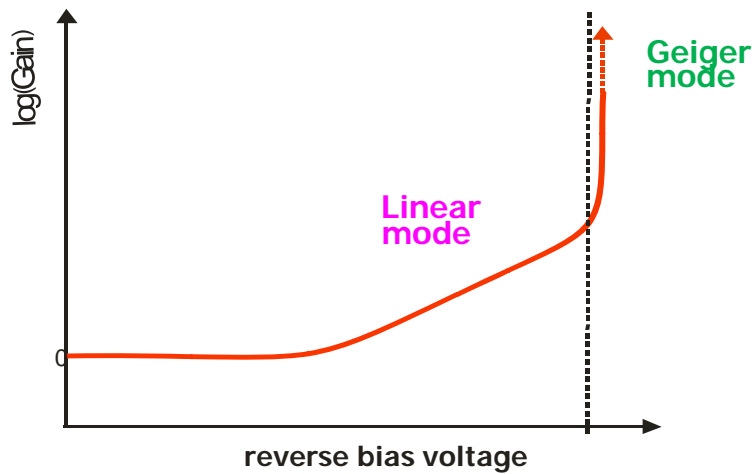
- Amplify signal



# ● Avalanche photodiode



**Linear/ Proportional mode**  
 Bias: slightly *BELOW* breakdown  
 Linear-mode: it's an *AMPLIFIER*  
 Gain: limited < 300 (1000)

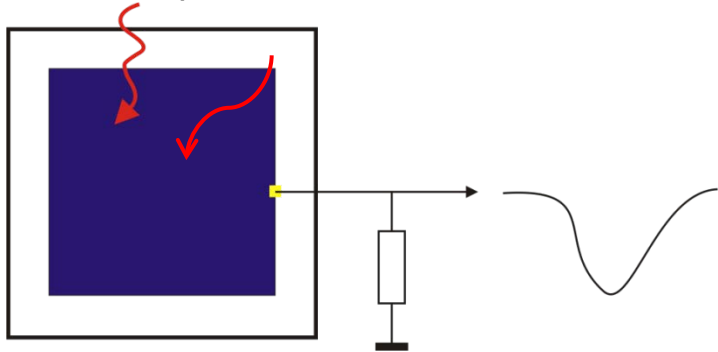


**Geiger mode**  
 Bias: (10%-20%) *ABOVE* breakdown voltage  
 Geiger-mode: it's a *BINARY* device!!  
 Gain: "*infinite*" !!

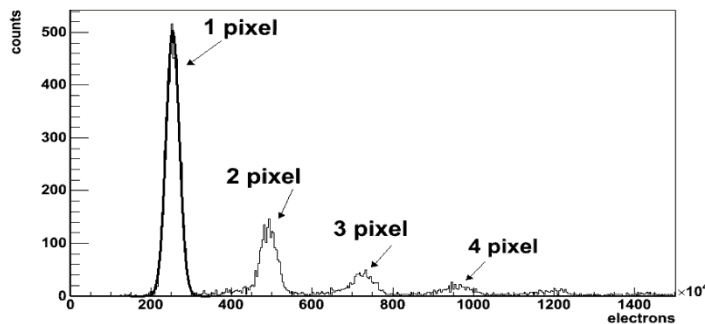
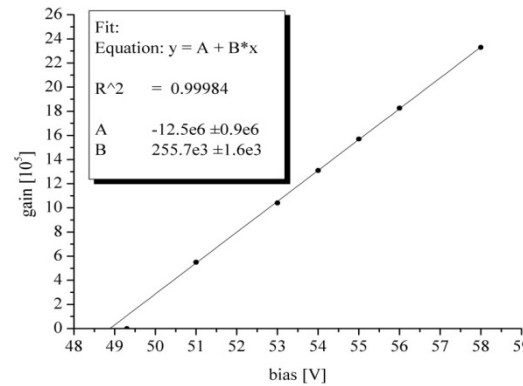
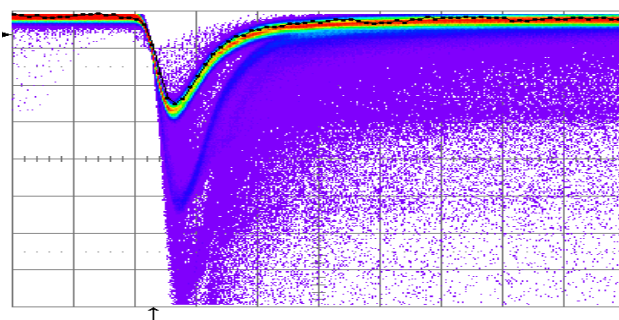
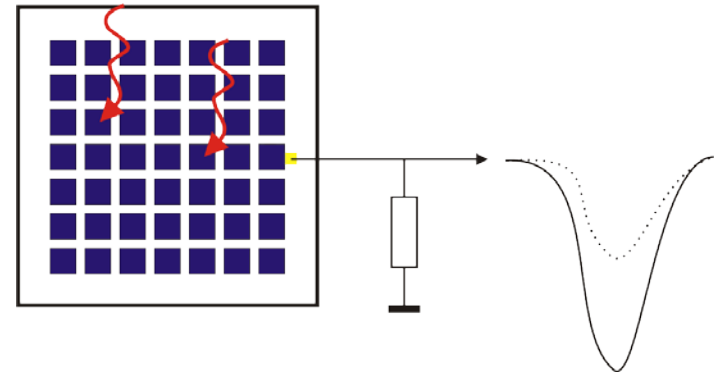


# ● Silicon photomultiplier

Avalanche photodiode



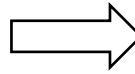
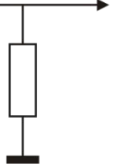
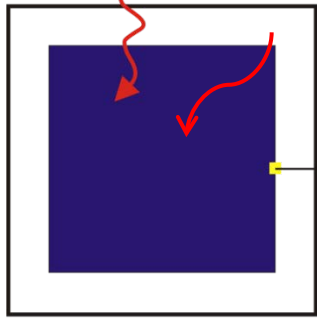
Silicon photomultiplier



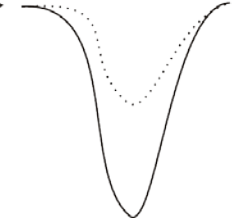
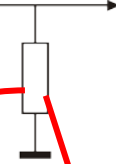
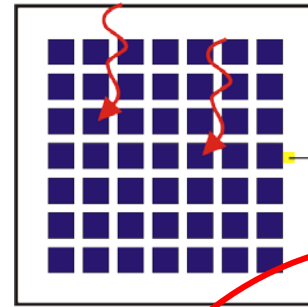
**Operating voltage:**  $\ll 100$  V  
**Gain:**  $10^5$  up to  $10^7$   
**dependence of Gain on Temp.:** 0.5% dG/dT

# ● Silicon photomultiplier

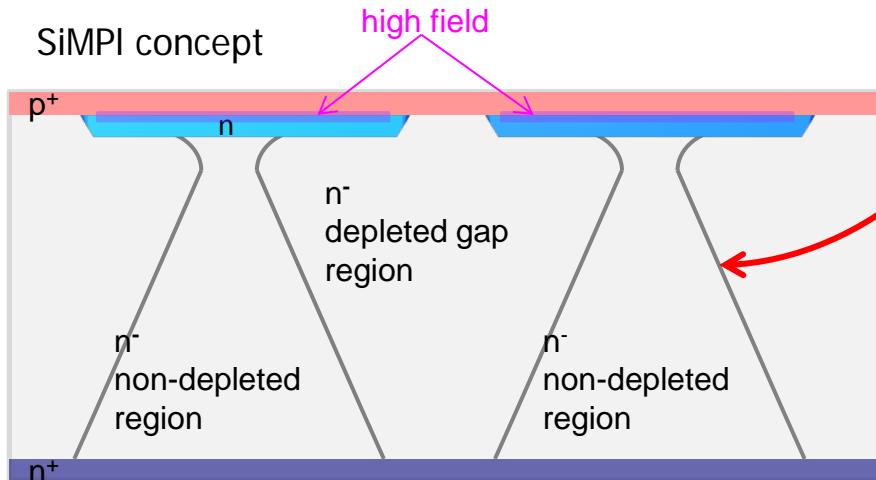
Avalanche photodiode



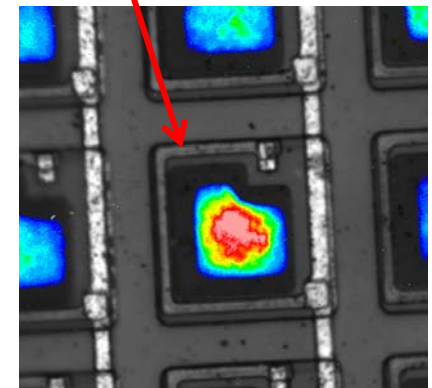
Silicon photomultiplier



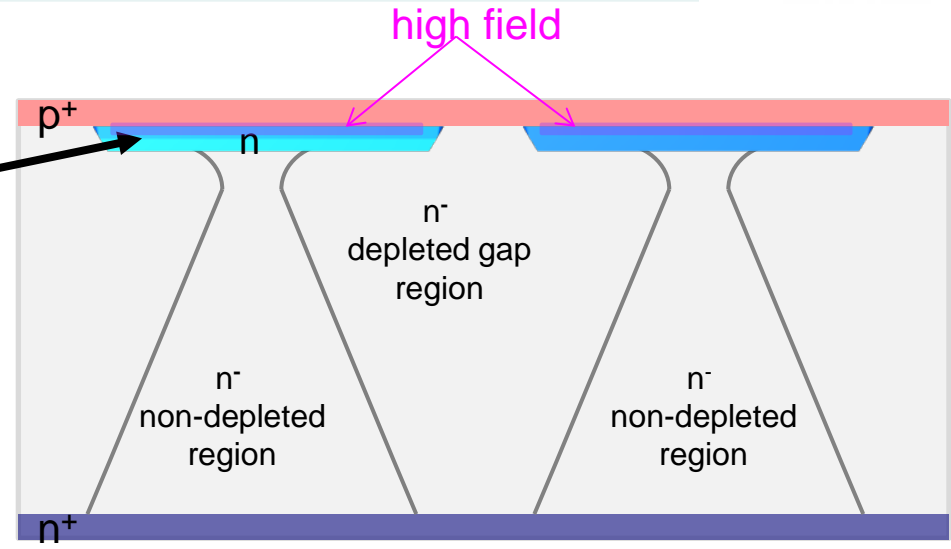
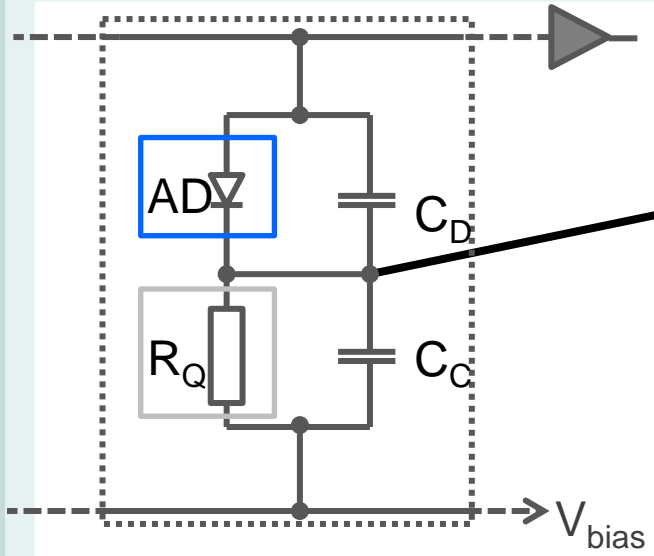
SiMPI concept



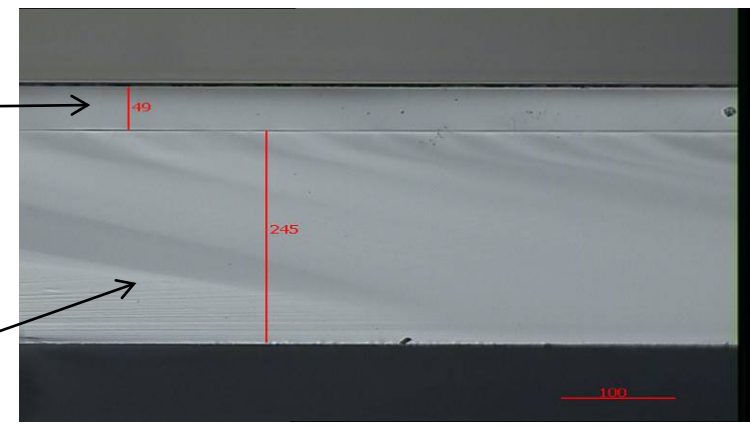
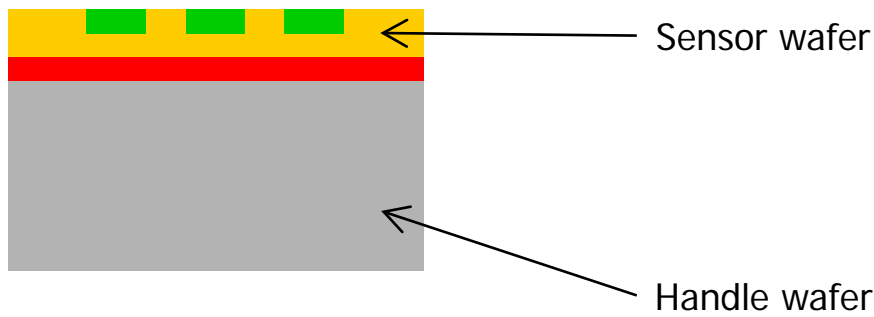
Conventional SiPMs



● SiPM cell components → SiMPI approach



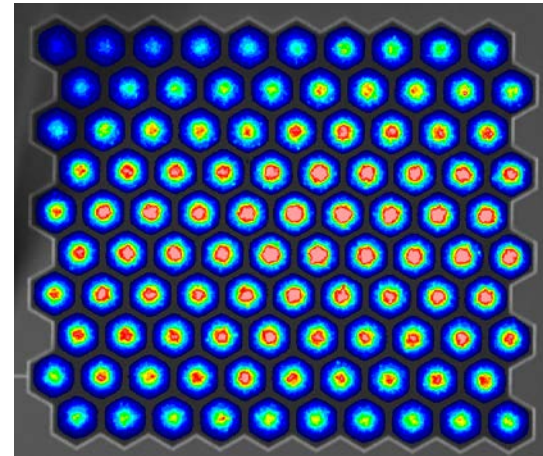
SOI wafers



## ● SiMPI : Advantages and Disadvantages

### Advantages:

- no need of polysilicon
- free entrance window for light, no metal necessary within the array
- coarse lithographic level
- simple technology
- inherent diffusion barrier against minorities in the bulk → less optical cross talk

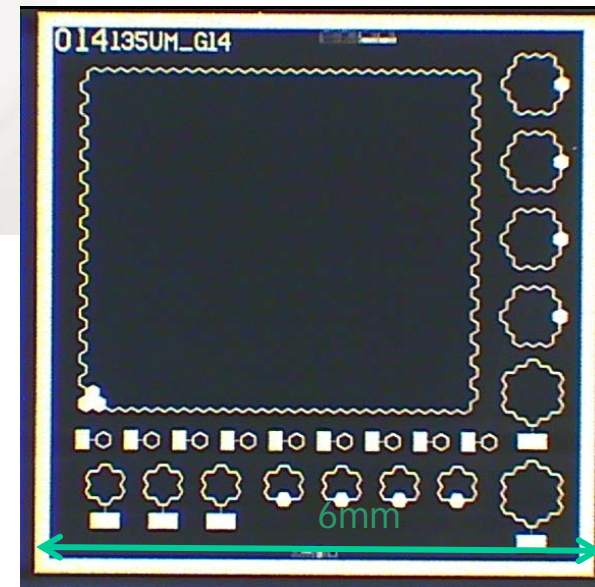
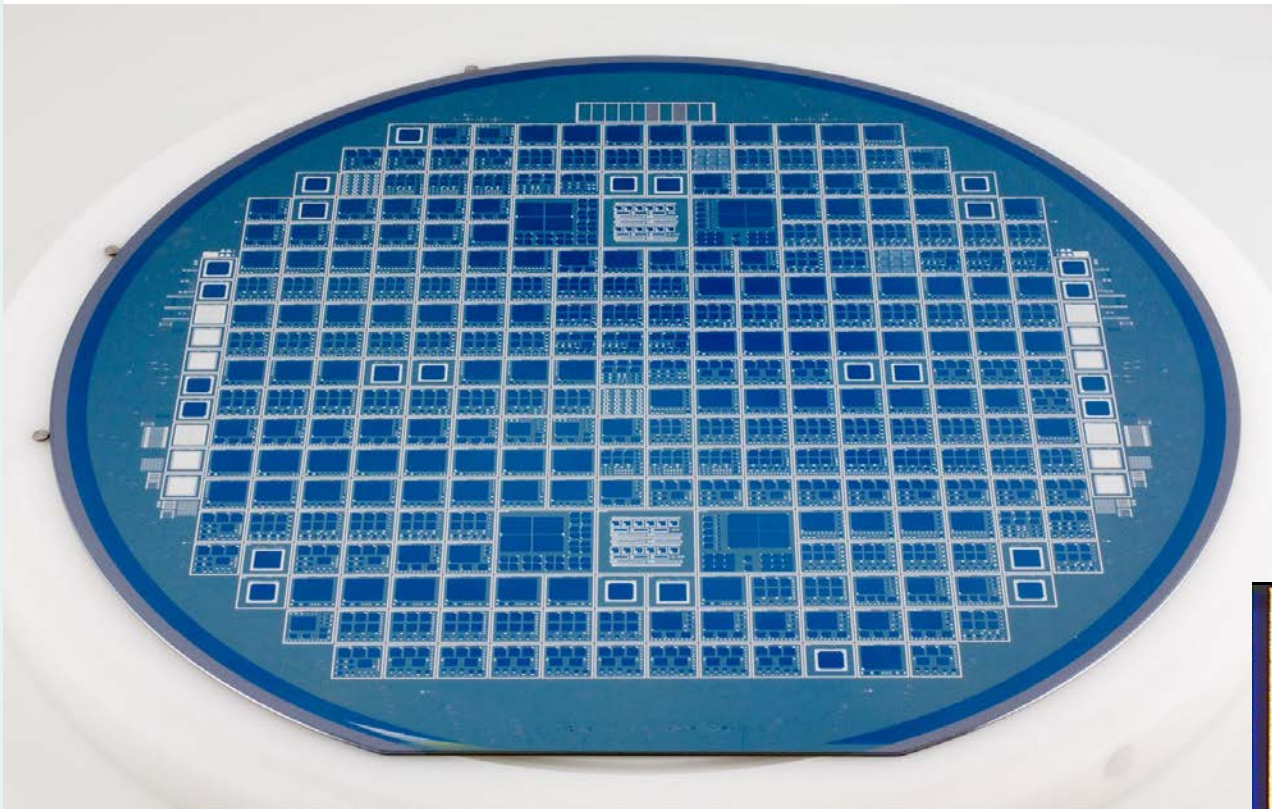


### Drawbacks:

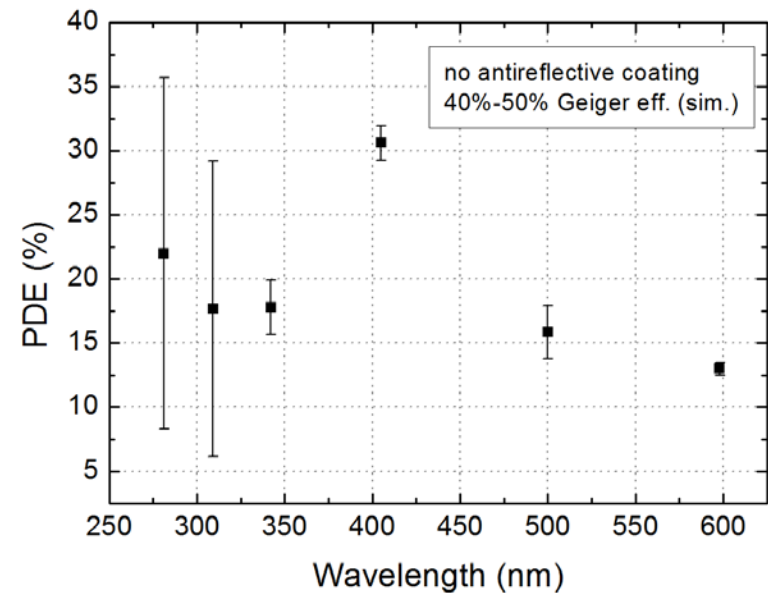
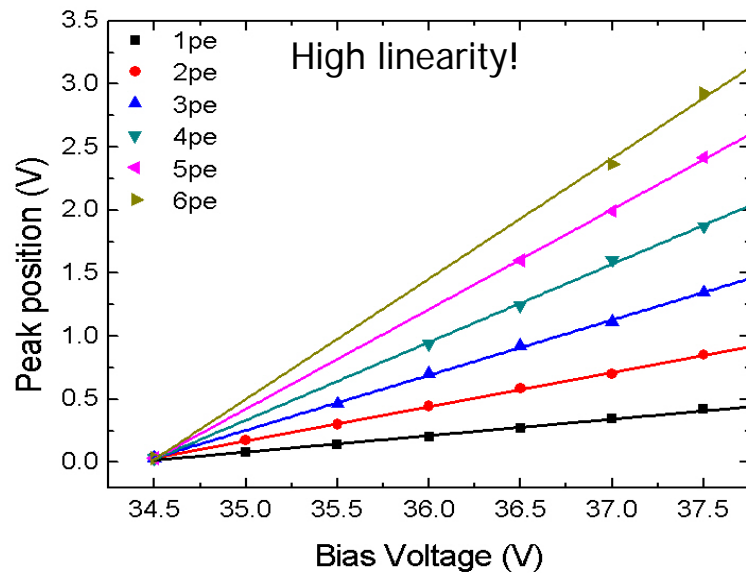
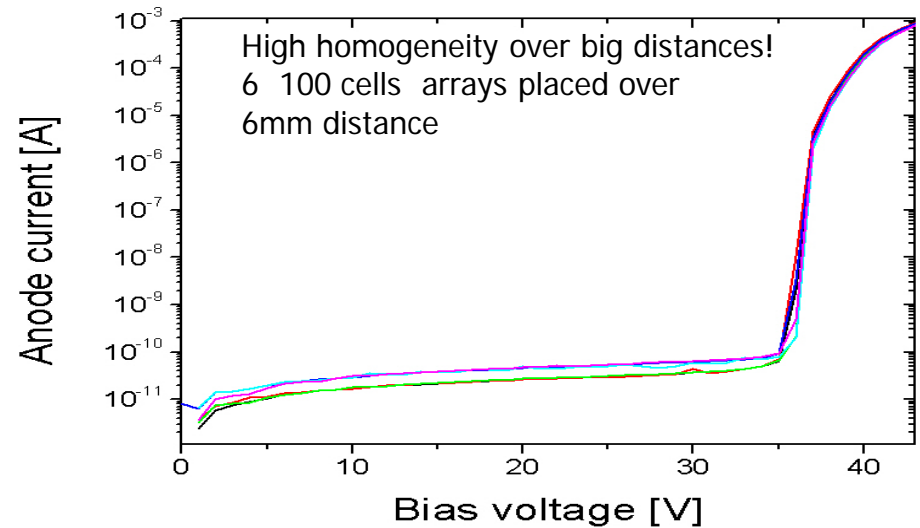
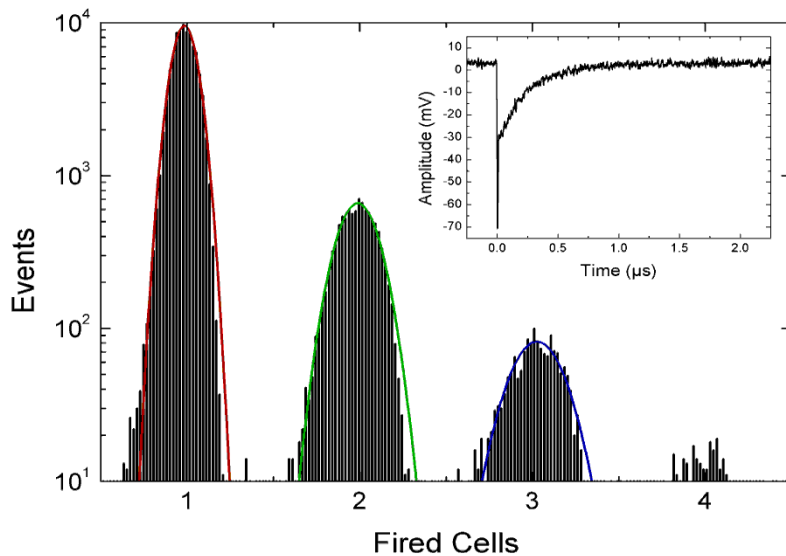
- required depth for vertical resistors does not match wafer thickness
- wafer bonding is necessary for big pixel sizes
- significant changes of cell size requires change of the material
- vertical 'resistor' is a JFET → parabolic IV → longer recovery times



- Prototype production



# ● Prototype production

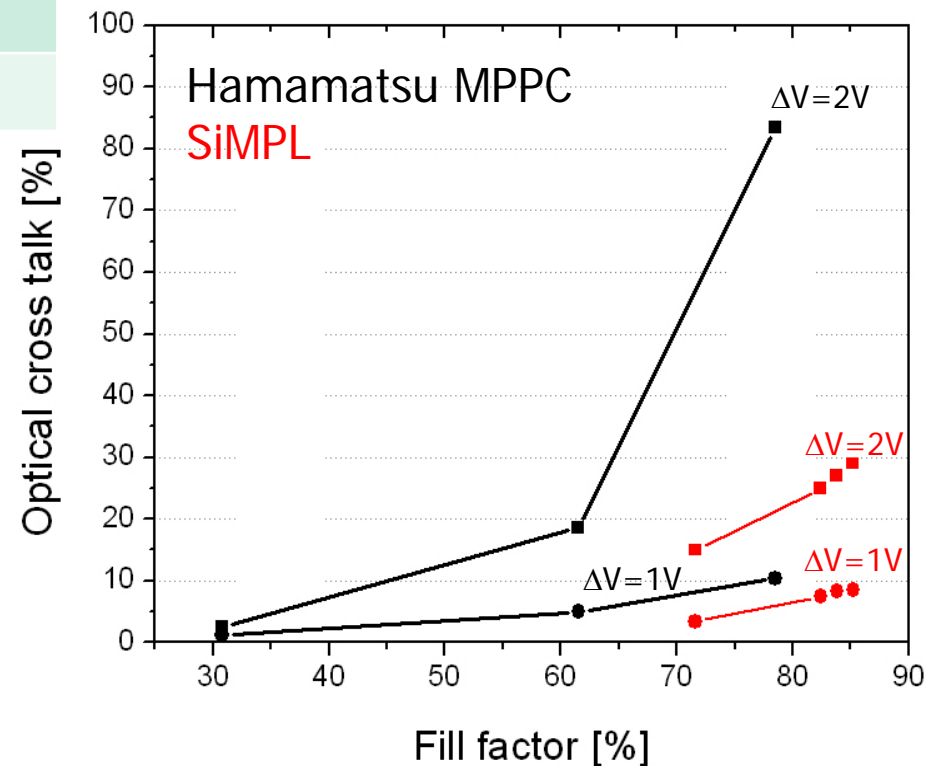


# ● Fill factor & Cross Talk

**Fill factor limited only by the cross talk suppression need!**

Pitch / Gap	Fill factor	Cross talk meas. ( $\Delta V=2V$ )
130 $\mu$ m / 10 $\mu$ m	85.2%	29%
130 $\mu$ m / 11 $\mu$ m	83.8%	27%
130 $\mu$ m / 12 $\mu$ m	82.4%	25%
130 $\mu$ m / 20 $\mu$ m	71.6%	15%

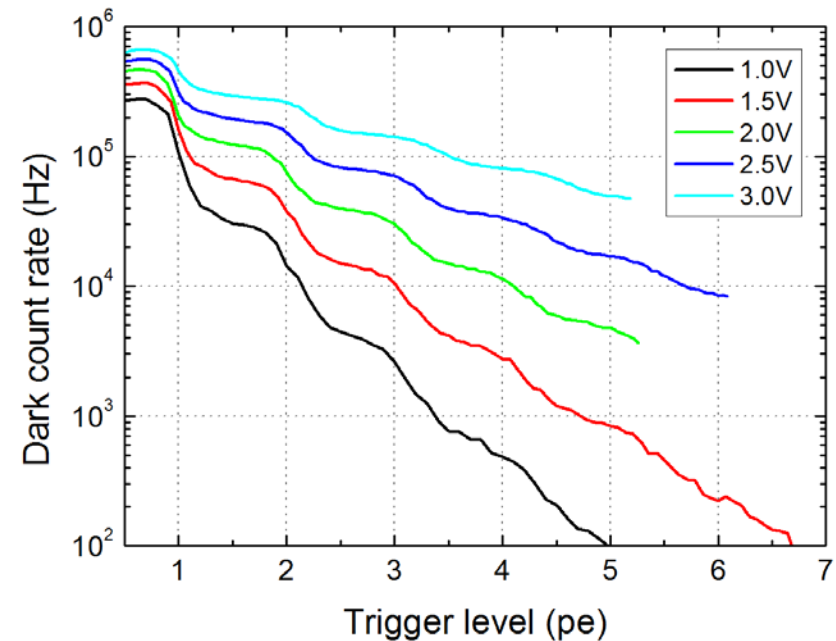
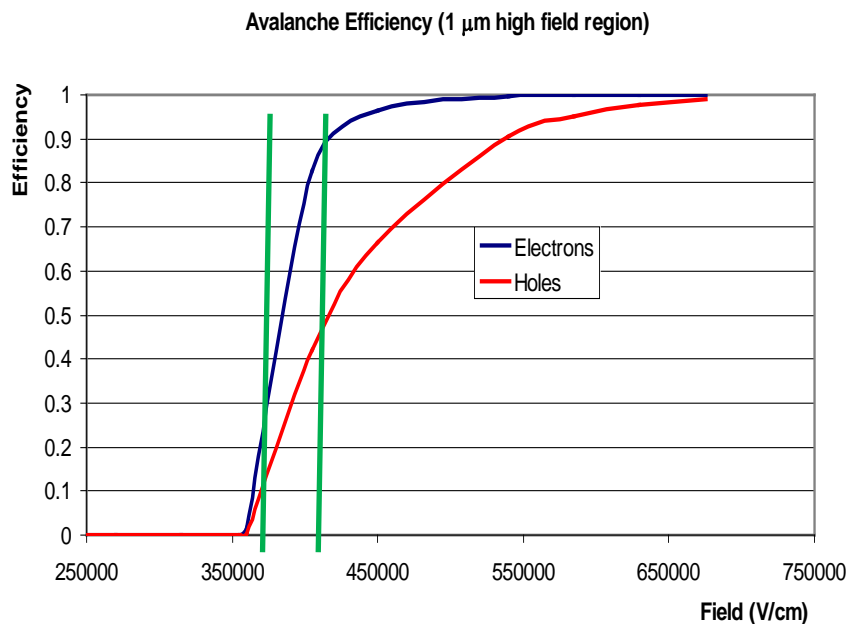
No special cross talk suppression technology applied just intrinsic property of SiMPL devices



# ● Detection of particles

## Detection of particles:

- High gain in the sensor
- Excellent time stamping due to avalanche process (sub-ns)
- Minimum ionizing particles generate about 80 e-h-pairs/ $\mu\text{m}$
- No need for high trigger efficiency



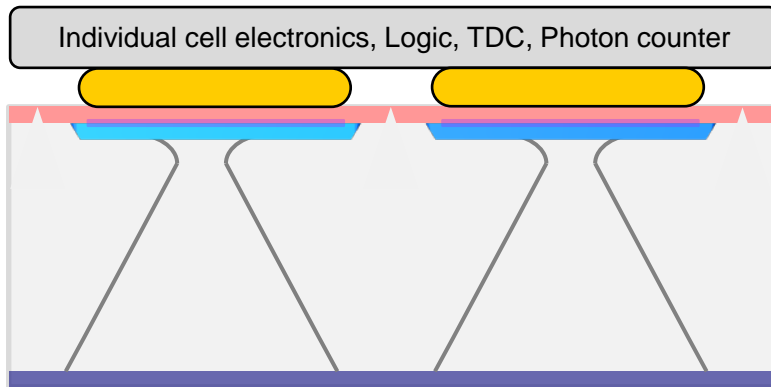
Reduction of dark rate and cross talk by order of magnitude



## ● Next generation SiMPI devices - DSiPMI – collaboration with DESY



### *Ultra fast particle tracker - High energy physics application*



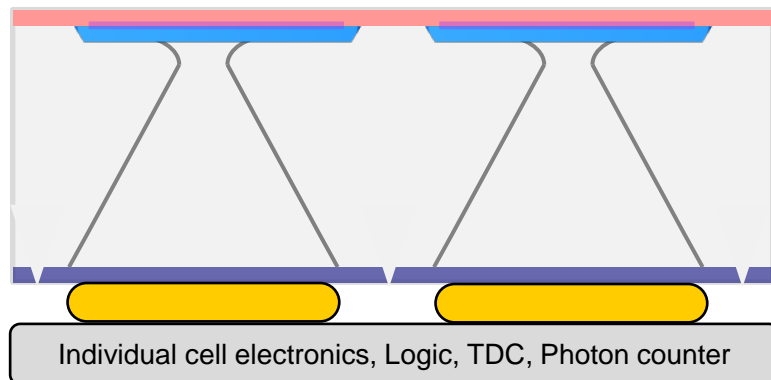
#### Sensor @ MPG HLL:

- Topologically flat surface
- High fill factor
- Adjustable resistor value  
Low RC -> very fast
- Single pixel readout
- Position sensitivity

#### ASIC @ DESY:

- Active recharge
- Ability to turn off noisy pixels
- Fast timing
- Pitch limited by the bump bonding
- Position resolving signal processing

### *Ultra fast single photon sensitive imager – Photon science*



#### Possible applications:

- Future trackers at colliders
- Detectors for hadron therapies
- X ray detectors
- PET detectors
- Adaptive optic sensors

# Summary

I showed :

- Some very attractive devices developed and produced at MPS Semiconductor Laboratory  
pnCCDs, DEPFETs , SiMPI ...
- Some of the potentials of those devices are used in current projects
- Still space to explore much more ...

Thank you for your attention ...